



PATENT  
Atty. Dkt. No. APPM/5351.Y1/CP/L/B/PJS

In re Application of:  
Mak et al.

Patent No.: 6,849,545

Issued: February 1, 2005

Serial No.: 09/885,609

Filed: June 20, 2001

For: SYSTEM AND METHOD TO  
FORM A COMPOSITE FILM  
STACK UTILIZING  
SEQUENTIAL DEPOSITION  
TECHNIQUES

Certificate of Correction Branch  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

§§ Group Art Unit: 2818  
§§ Examiner: Renee R. Berry  
§§

*Certificate*  
*SEP 13 2006*  
*of Correction*

CERTIFICATE OF MAILING 37 CFR 1.8	
I hereby certify that this correspondence is being deposited on <u>9/7/06</u> , 2006 with the United States Postal Service as First Class Mail in an envelope addressed to: Certificate of Correction Branch, Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.	
<u>9/7/06</u>	<u>Kim Z. Zhs</u>
Date	Signature

Dear Sir:

#### REQUEST FOR CORRECTED PATENT

Attached is a certificate of correction for correcting several errors throughout the printed patent. However, because of the nature of the errors, applicants request that the Director issue a corrected patent, if appropriate, in lieu of the certificate of correction (MPEP §1480; 35 USC 254 and 37 CFR 1.322(b)).

Some of the missing references were cited by the Applicant in an Information Disclosure Statement filed on March 29, 2002. It appears that these references were lost, and thus they do not appear on the printed patent. Attached is a copy of the PTO-1449 as originally submitted on March 29, 2002, as well as a copy of the stamped return receipt postcard showing evidence that the Patent Office acknowledged receipt of this Information Disclosure Statement.

Some of the missing references were cited by the Applicant in an Information Disclosure Statement filed on May 2, 2002. It appears that these references were

*SEP 13 2006*  
*SEP 13 2006*

lost, and thus they do not appear on the printed patent. Attached is a copy of the PTO-1449 as originally submitted on May 2, 2002, as well as a copy of the stamped return receipt postcard showing evidence that the Patent Office acknowledged receipt of this Information Disclosure Statement.

The missing reference US-2003/0089308 was initialed by the examiner on July 10, 2004 in the Notice of Allowability dated August 2, 2004. Attached is a copy of the PTO/SB/08a showing the missing reference initialed by the examiner.

The remaining missing references were cited by the examiner in the Office Action dated March 14, 2003. Attached is a copy of the PTO-892 showing the missing references.

The drawings that appear in the printed patent are the informal drawings. Formal drawings were submitted on November 27, 2001, which appear to have been lost or overlooked. Attached is a copy of the transmittal form, transmittal letter, and formal drawings as submitted on November 27, 2001, as well as a copy of the stamped return receipt postcard showing evidence that the Patent Office acknowledged receipt of the drawings.

Applicants submit that the errors mentioned above were not made by the applicants, but were made during the printing of the patent. Accordingly, the Applicants believe that no fee is due for the corrected patent at this time.

Respectfully submitted,



---

Keith M. Tackett  
Registration No. 32,008  
PATTERSON & SHERIDAN, L.L.P.  
3040 Post Oak Blvd. Suite 1500  
Houston, TX 77056  
Telephone: (713) 623-4844  
Facsimile: (713) 623-4846  
Agent for Applicant(s)

**UNITED STATES PATENT AND TRADEMARK OFFICE**  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,849,545

Page 1 of 18

APPLICATION NO. : 09/885,609

DATED : Feb. 1, 2005

INVENTOR(S) : Alfred W. MAK, Mei CHANG, Jeong Soo BYUN, Hua CHUNG, Ashok SINHA, Moris KORI

It is certified that error appears in the above-identified patent and that said Letters Patent  
are hereby corrected as shown below:

On the Cover of the Patent

Item [56], References Cited, U.S. PATENT DOCUMENTS: Please include the following references:

4,486,487	12/1984	Skarp .....	428/216
4,829,022	5/1989	Kobayashi et al. ....	437/107
4,834,831	5/1989	Nishizawa et al. ....	156/611
4,838,983	6/1989	Schumaker et al.....	156/613
4,838,993	6/1989	Aoki et al. ....	156/643
4,859,625	8/1989	Nishizawa et al. ....	437/81
4,927,670	5/1990	Erbil .....	427/255.3
4,931,132	6/1990	Aspnes et al. ....	156/601
4,960,720	10/1990	Shimbo .....	437/105
4,975,252	12/1990	Nishizawa et al. ....	422/245
5,013,683	5/1991	Petroff et al. ....	437/110
5,085,885	2/1992	Foley et al. ....	477/38
5,091,320	2/1992	Aspnes et al. ....	437/8
5,246,536	9/1993	Nishizawa et al. ....	156/610
5,254,207	10/1993	Nishizawa et al. ....	156/601
5,296,403	3/1994	Nishizawa et al. ....	437/133
5,311,055	5/1994	Goodman et al. ....	257/593
5,316,615	5/1994	Copel .....	117/95
5,348,911	9/1994	Jurgensen et al. ....	117/91
5,438,952	8/1995	Otsuka .....	117/84
5,439,876	8/1995	Graf et al. ....	505/447
5,441,703	8/1995	Jurgensen .....	422/129
5,455,072	10/1995	Bension et al. ....	427/255.7
5,469,806	11/1995	Mochizuki et al. ....	117/97
5,503,875	4/1996	Imai et al. ....	427/255.3
5,521,126	5/1996	Okamura et al. ....	437/235
5,527,733	6/1996	Nishizawa et al. ....	437/160
5,540,783	7/1996	Eres et al. ....	118/725
5,601,651	2/1997	Watabe .....	118/715
5,616,181	4/1997	Yamamoto et al. ....	118/723ER
5,641,984	6/1997	Aftergut et al. ....	257/433
5,644,128	7/1997	Wollnik et al. ....	250/251
5,707,880	1/1998	Aftergut et al. ....	437/3
5,747,113	5/1998	Tsai .....	427/255.5
5,749,974	5/1998	Habuka et al. ....	118/725

MAILING ADDRESS OF SENDER (Please do not use customer number below):

Keith M. Tackett  
 PATTERSON & SHERIDAN, L.L.P.  
 3040 Post Oak Blvd., Suite 1500  
 Houston, TX 77056-6582

This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

**UNITED STATES PATENT AND TRADEMARK OFFICE**  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,849,545

Page 2 of 18

APPLICATION NO. : 09/885,609

DATED : Feb. 1, 2005

INVENTOR(S) : Alfred W. MAK, Mei CHANG, Jeong Soo BYUN, Hua CHUNG, Ashok SINHA, Moris KORI

It is certified that error appears in the above-identified patent and that said Letters Patent  
are hereby corrected as shown below:

5,796,116	8/1998	Nakata et al. ....	257/66
5,807,792	9/1998	Ilg et al. ....	438/758
5,830,270	11/1998	McKee et al. ....	117/106
5,835,677	11/1998	Li et al. ....	392/401
5,855,675	1/1999	Doering et al. ....	118/719
5,858,102	1/1999	Tsai .....	118/719
5,904,565	5/1999	Nguyen et al. ....	438/687
5,923,056	7/1999	Lee et al. ....	257/192
5,923,985	7/1999	Aoki et al. ....	438/301
5,925,574	7/1999	Aoki et al. ....	437/31
5,942,040	8/1999	Kim et al. ....	118/726
5,947,710	9/1999	Cooper et al. ....	418/63
5,972,430	10/1999	DiMeo, Jr. et al. ....	427/255.32
6,001,669	12/1999	Gaines et al. ....	438/102
6,174,377	1/2001	Doering et al. ....	118/729
6,174,809	1/2001	Kang et al. ....	438/682
6,203,613	3/2001	Gates et al. ....	117/104
6,207,302	3/2001	Sugiura et al. ....	428/690
6,248,605	6/2001	Harkonen et al. ....	438/29
6,270,572	8/2001	Kim et al. ....	117/93
6,287,965	9/2001	Kang et al. ....	438/648
6,291,876	9/2001	Stumborg et al. ....	257/632
6,305,314	10/2001	Sneh et al. ....	118/723 R
6,306,216	10/2001	Kim et al. ....	118/725
6,316,098	11/2001	Yitzchaik et al. ....	428/339
2001/0000866	5/2001	Sneh et al. ....	118/723 R
2001/0009140	7/2001	Bondestam et al. ....	118/725
2001/0011526	8/2001	Doering et al. ....	118/729
2001/0031562	10/2001	Raaijmakers et al. ....	438/770
2001/0034123	10/2001	Jeon et al. ....	438/643
4,813,846	03/1989	Helms. ....	414/744.1
4,917,556	04/1990	Stark et al. ....	414/217
4,951,601	08/1990	Maydan et al. ....	118/719
5,000,113	03/1991	Wang et al. ....	118/723
5,028,565	07/1991	Chang et al. ....	437/192
5,173,474	12/1992	Connell et al. ....	505/1
5,186,718	02/1993	Tepman et al. ....	29/25.01
5,205,077	04/1993	Wittstock. ....	51/165 R
5,234,561	08/1993	Randhawa et al. ....	204/192.38

MAILING ADDRESS OF SENDER (Please do not use customer number below):

Keith M. Tackett  
PATTERSON & SHERIDAN, L.L.P.  
3040 Post Oak Blvd., Suite 1500  
Houston, TX 77056-6582

This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

**UNITED STATES PATENT AND TRADEMARK OFFICE**  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,849,545

Page 3 of 18

APPLICATION NO. : 09/885,609

DATED : Feb. 1, 2005

INVENTOR(S) : Alfred W. MAK, Mei CHANG, Jeong Soo BYUN, Hua CHUNG, Ashok SINHA, Moris KORI

It is certified that error appears in the above-identified patent and that said Letters Patent  
are hereby corrected as shown below:

5,259,881	11/1993	Edwards et al..... 118/719
5,286,296	02/1994	Sato et al..... 118/719
5,580,380	12/1996	Liu et al..... 117/86
5,609,689	03/1997	Kato et al..... 118/719
5,667,592	09/1997	Boitnott et al..... 118/719
5,674,786	10/1997	Turner et al..... 437/225
5,695,564	12/1997	Imahashi ..... 118/719
5,730,801	03/1998	Tepman et al..... 118/719
5,788,447	08/1998	Yonemitsu et al..... 414/217
5,788,799	08/1998	Steger et al..... 156/345
5,801,634	09/1998	Young et al..... 340/635
5,856,219	01/1999	Naito et al..... 438/241
5,866,213	02/1999	Foster et al..... 427/573
5,866,795	02/1999	Wang et al..... 73/1.36
5,882,165	03/1999	Maydan et al..... 414/217
5,882,413	03/1999	Beaulieu et al..... 118/719
5,928,389	07/1999	Jevtic..... 29/25.01
6,051,286	04/2000	Zhao et al..... 427/576
6,062,798	05/2000	Muka..... 414/416
6,071,808	06/2000	Merchant et al..... 438/633
6,084,302	07/2000	Sandhu..... 257/751
6,086,677	07/2000	Umotoy et al..... 118/715
6,110,556	08/2000	Bang et al..... 428/64.1
6,117,244	09/2000	Bang et al..... 118/715
6,140,237	10/2000	Chan et al..... 438/687
6,140,238	10/2000	Kitch..... 438/687
6,143,659	11/2000	Leem..... 438/688
6,144,060	11/2000	Park et al..... 25/310
6,158,446	12/2000	Mohindra et al..... 134/25.4
6,206,967	03/2001	Mak et al ..... 118/666
6,271,148	08/2001	Kao et al ..... 438/727
2001/0041250	11/2001	Werkhoven et al..... 428/212
2003/0089308	5/2003	Raaijmakers
5,393,565	6/1993	Suzuki et al. .... 427/255.2
5,942,799	11/1997	Danek et al. .... 257/751
6,495,449	5/2000	Nguyen ..... 438/627

MAILING ADDRESS OF SENDER (Please do not use customer number below):

Keith M. Tackett  
PATTERSON & SHERIDAN, L.L.P.  
3040 Post Oak Blvd., Suite 1500  
Houston, TX 77056-6582

This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

**UNITED STATES PATENT AND TRADEMARK OFFICE**  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,849,545

Page 4 of 18

APPLICATION NO. : 09/885,609

DATED : Feb. 1, 2005

INVENTOR(S) : Alfred W. MAK, Mei CHANG, Jeong Soo BYUN, Hua CHUNG, Ashok SINHA, Moris KORI

It is certified that error appears in the above-identified patent and that said Letters Patent  
are hereby corrected as shown below:

Item [56], References Cited, FOREIGN PATENT DOCUMENTS: Please include the following references:

01/66832 A2	09/2001	WO	C30B	16/44
01/40541 A1	06/2001	WO	C23C	16/40
01/36702 A1	05/2001	WO	C23C	16/00
01/29893 A1	04/2001	WO	H01L	21/768
01/29891 A1	04/2001	WO	H01L	21/768
01/29280 A1	04/2001	WO	C23C	16/32
01/27347 A1	04/2001	WO	C23C	16/44
01/27346 A1	04/2001	WO	C23C	16/44
01/15220 A1	03/2001	WO	H01L	21/768
00/79576 A1	12/2000	WO	H01L	21/205
00/79019 A1	12/2000	WO	C23C	16/00
00/63957 A1	10/2000	WO	H01L	21/205
00/54320 A1	09/2000	WO	H01L	21/44
00/16377 A2	03/2000	WO	H01L	---
00/15881 A2	03/2000	WO	C30B	---
99/41423 A2	08/1999	WO	C23C	---
96/18756 A1	06/1996	WO	C23C	16/08
96/17107 A1	06/1996	WO	C23C	16/44
93/02111 A1	02/1993	WO	C08F	4/78
0 442 490 A1	08/1991	EP	C30B	25/02
0 344 352 A1	12/1989	EP	H01L	39/24
62-091495 A	04/1987	JP	C30B	25/02
60-065712 A	04/1985	JP	C01B	33/113
03-048421	03/1991	JP	H01L	21/302
03-286531	12/1991	JP	H01L	21/316
04-031396 A	02/1992	JP	C30B	25/14
06-291048	10/1994	JP	H01L	21/205
08-264530	10/1996	JP	H01L	21/3205
11-269652	10/1999	JP	C23C	16/44
2001-62244	03/2001	JP	B01D	53/34
198 20 147	07/1999	DE	H01L	21/3205
196 27 017	01/1997	DE	H01L	21/283
2 626 110	07/1989	FR	H01L	39/24
2 692 597	12/1993	FR	C23C	16/00
2 355 727	05/2001	GB	C23C	16/44
58-098917	06/13/1983	JP	H01L	21/205
58-100419	06/15/1983	JP	H01L	21/20

MAILING ADDRESS OF SENDER (Please do not use customer number below):

Keith M. Tackett  
PATTERSON & SHERIDAN, L.L.P.  
3040 Post Oak Blvd., Suite 1500  
Houston, TX 77056-6582

This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

**UNITED STATES PATENT AND TRADEMARK OFFICE**  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,849,545

Page 5 of 18

APPLICATION NO. : 09/885,609

DATED : Feb. 1, 2005

INVENTOR(S) : Alfred W. MAK, Mei CHANG, Jeong Soo BYUN, Hua CHUNG, Ashok SINHA, Moris KORI

It is certified that error appears in the above-identified patent and that said Letters Patent  
are hereby corrected as shown below:

61-035847	02/20/1986	JP	B01J	19/08
61-210623	09/18/1986	JP	H01L	21/205
62-069508	03/30/1987	JP	H01L	21/203
62-141717	06/25/1987	JP	H01L	21/203
62-167297	07/23/1987	JP	C30B	29/40
62-171999	07/28/1987	JP	C30B	29/40
62-232919	10/13/1987	JP	H01L	21/205
63-062313	03/18/1988	JP	H01L	21/203
63-085098	04/15/1988	JP	C30B	21/40
63-090833	04/21/1988	JP	H01L	21/365
63-222420	09/16/1988	JP	H01L	21/205
63-222421	09/16/1988	JP	H01L	21/205
63-227007	09/21/1988	JP	H01L	21/205
63-252420	10/19/1988	JP	H01L	21/205
63-266814	11/02/1988	JP	H01L	21/205
64-009895	01/13/1989	JP	C30B	29/40
64-009896	01/13/1989	JP	C30B	29/40
64-009897	01/13/1989	JP	C30B	29/40
64-037832	02/08/1989	JP	H01L	21/205
64-082615	03/28/1989	JP	H01L	21/205
64-082617	03/28/1989	JP	H01L	21/205
64-082671	03/28/1989	JP	H01L	29/78
64-082676	03/28/1989	JP	H01L	29/80
64-090524	04/07/1989	JP	H01L	21/205
01-103982	04/21/1989	JP	C30B	23/08
01-103996	04/21/1989	JP	C30B	29/40
01-117017	05/09/1989	JP	H01L	21/203
01-143221	06/05/1989	JP	H01L	21/314
01-143233	06/05/1989	JP	H01L	21/76
01-154511	06/16/1989	JP	H01L	21/20
01-236657	09/21/1989	JP	H01L	29/80
01-245512	09/29/1989	JP	H01L	21/205
01-264218	10/20/1989	JP	H01L	21/205
01-270593	10/27/1989	JP	C30B	25/02
01-272108	10/31/1989	JP	H01L	21/203
01-290221	11/22/1989	JP	H01L	21/205
01-290222	11/22/1989	JP	H01L	21/205
01-296673	11/30/1989	JP	H01L	29/88
01-303770	12/07/1989	JP	H01L	39/24
01-305894	12/11/1989	JP	C30B	23/08

MAILING ADDRESS OF SENDER (Please do not use customer number below):

Keith M. Tackett  
PATTERSON & SHERIDAN, L.L.P.  
3040 Post Oak Blvd., Suite 1500  
Houston, TX 77056-6582

This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

SEP 13 2006

**UNITED STATES PATENT AND TRADEMARK OFFICE**  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,849,545

Page 6 of 18

APPLICATION NO. : 09/885,609

DATED : Feb. 1, 2005

INVENTOR(S) : Alfred W. MAK, Mei CHANG, Jeong Soo BYUN, Hua CHUNG, Ashok SINHA, Moris KORI

It is certified that error appears in the above-identified patent and that said Letters Patent  
are hereby corrected as shown below:

01-313927	12/19/1989	JP	H01L	21/205
02-012814	01/17/1990	JP	H01L	21/205
02-014513	01/18/1990	JP	H01L	21/205
02-017634	01/22/1990	JP	H01L	21/225
02-063115	03/02/1990	JP	H01L	21/20
02-074029	03/14/1990	JP	H01L	21/205
02-074587	03/14/1990	JP	C30B	23/08
02-106822	04/18/1990	JP	H01B	13/00
02-129913	05/18/1990	JP	H01L	21/205
02-162717	06/22/1990	JP	H01L	21/20
02-172895	07/04/1990	JP	C30B	29/36
02-196092	08/02/1990	JP	C30B	25/14
02-203517	08/13/1990	JP	H01L	21/205
02-230690	09/13/1990	JP	H05B	33/10
02-230722	09/13/1990	JP	H01L	21/205
02-246161	10/01/1990	JP	H01L	29/784
02-264491	10/29/1990	JP	H01S	3/18
02-283084	11/20/1990	JP	H01S	3/18
02-304916	12/18/1990	JP	H01L	21/205
03-019211	01/28/1991	JP	H01L	21/205
03-022569	01/30/1991	JP	H01L	29/804
03-023294	01/31/1991	JP	C30B	25/18
03-023299	01/31/1991	JP	C30B	29/40
03-044967	02/26/1991	JP	H01L	29/48
03-070124	03/26/1991	JP	H01L	21/205
03-185716	08/13/1991	JP	H01L	21/205
03-208885	09/12/1991	JP	C30B	23/02
03-234025	10/18/1991	JP	H01L	21/318
03-286522	12/17/1991	JP	H01L	21/205
04-031391	02/03/1992	JP	C30B	23/08
04-031396	02/03/1992	JP	C30B	25/14
04-100292	04/02/1992	JP	H01S	3/18
04-111418	04/13/1992	JP	H01L	21/205
04-132214	05/06/1992	JP	H01L	21/205
04-132681	05/06/1992	JP	C30B	25/14
04/151822	05/25/1992	JP	H01L	21/205
04-162418	06/05/1992	JP	H01L	21/205
04-175299	06/23/1992	JP	C30B	29/68
04-186824	07/03/1992	JP	H01L	21/205
04-212411	08/04/1992	JP	H01L	21/203
04-260696	09/16/1992	JP	C30B	29/40

MAILING ADDRESS OF SENDER (Please do not use customer number below):

Keith M. Tackett  
 PATTERSON & SHERIDAN, L.L.P.  
 3040 Post Oak Blvd., Suite 1500  
 Houston, TX 77056-6582

This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

**UNITED STATES PATENT AND TRADEMARK OFFICE**  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,849,545

Page 7 of 18

APPLICATION NO. : 09/885,609

DATED : Feb. 1, 2005

INVENTOR(S) : Alfred W. MAK, Mei CHANG, Jeong Soo BYUN, Hua CHUNG, Ashok SINHA, Moris KORI

It is certified that error appears in the above-identified patent and that said Letters Patent  
are hereby corrected as shown below:

04-273120	09/29/1992	JP	H01L	21/20
04-285167	10/09/1992	JP	C23C	14/54
04-291916	10/16/1992	JP	H01L	21/205
04-325500	11/13/1992	JP	C30B	33/00
04-328874	11/17/1992	JP	H01L	29/804
05-029228	02/05/1993	JP	H01L	21/205
05-047665	02/26/1993	JP	H01L	21/205
05-047666	02/26/1993	JP	H01L	21/205
05-047668	02/26/1993	JP	H01L	21/205
05-074717	03/26/1993	JP	H01L	21/205
05-074724	03/26/1993	JP	H01L	21/205
05-102189	04/23/1993	JP	H01L	21/336
05-160152	06/25/1993	JP	H01L	21/336
05-175143	07/13/1993	JP	H01L	21/205
05-175145	07/13/1993	JP	H01L	21/205
05-182906	07/23/1993	JP	H01L	21/20
05-186295	07/27/1993	JP	C30B	25/02
05-206036	08/13/1993	JP	H01L	21/205
05-234899	09/10/1993	JP	H01L	21/205
05-235047	09/10/1993	JP	H01L	21/338
05-251339	09/28/1993	JP	H01L	21/20
05-270997	10/19/1993	JP	C30B	29/68
05-283336	10/29/1993	JP	H01L	21/20
05-291152	11/05/1993	JP	H01L	21/205
05-304334	11/16/1993	JP	H01L	3/18
05-343327	12/24/1993	JP	H01L	21/205
05-343685	12/24/1993	JP	H01L	29/784
06-045606	02/18/1994	JP	H01L	29/784
06-132236	05/13/1994	JP	H01L	21/205
06-177381	06/24/1994	JP	H01L	29/784
06-196809	07/15/1994	JP	H01S	3/18
06-222388	08/12/1994	JP	G02F	1/136
06-224138	08/12/1994	JP	H01L	21/205
06-230421	08/19/1994	JP	G02F	1/136
06-252057	09/09/1994	JP	H01L	21/205
07-070752	03/14/1995	JP	C23C	16/40
07-086269	03/13/1995	JP	H01L	21/314
07-086269	03/13/1995	JP	H01L	21/314
08-181076	07/12/1996	JP	H01L	21/205
08-245291	09/24/1996	JP	C30B	25/14

MAILING ADDRESS OF SENDER (Please do not use customer number below):

Keith M. Tackett  
 PATTERSON & SHERIDAN, L.L.P.  
 3040 Post Oak Blvd., Suite 1500  
 Houston, TX 77056-6582

This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

SEP 1 3 2005

**UNITED STATES PATENT AND TRADEMARK OFFICE**  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,849,545

Page 8 of 18

APPLICATION NO. : 09/885,609

DATED : Feb. 1, 2005

INVENTOR(S) : Alfred W. MAK, Mei CHANG, Jeong Soo BYUN, Hua CHUNG, Ashok SINHA, Moris KORI

It is certified that error appears in the above-identified patent and that said Letters Patent  
are hereby corrected as shown below:

09-260786	10/03/1997	JP	H01S	3/18
09-293681	11/11/1997	JP	H01L	21/205
10-188840	07/21/1998	JP	H01J	29/18
10-190128	07/21/1998	JP	H01S	3/18
10-308283	11/17/1998	JP	H05B	33/22
11-269652	10/05/1999	JP	C23C	16/44
2000-031387	01/28/2000	JP	H01L	27/04
2000-058777	02/25/2000	JP	H01L	27/108
2000-068072	03/03/2000	JP	H05B	33/22
2000-087029	03/28/2000	JP	C09K	11/08
2000-138094	05/16/2000	JP	H05B	33/10
2000-218445	08/08/2000	JP	B23P	6/00
2000-319772	11/21/2000	JP	C23C	14/24
2000-319772	03/28/2000	JP	C23C	16/00
2000-340883	12/08/2000	JP	H01S	5/125
2000-353666	12/19/2000	JP	H01L	21/205
2001-020075	01/23/2001	JP	C23C	16/44
2001-152339	06/05/2001	JP	C23C	16/40
2001-172767	06/26/2001	JP	C23C	16/40
2001-189312	07/10/2001	JP	H01L	21/316
2001-217206	08/10/2001	JP	H01L	21/285
2001-220287	08/14/2001	JP	C30B	25/02
2001-220294	08/14/2001	JP	C30B	29/20
2001-240972	09/04/2001	JP	C23C	16/458
2001-254181	09/18/2001	JP	C23C	16/46
2001-284042	10/12/2001	JP	H05B	33/04
2001-303251	10/31/2001	JP	C23C	16/44
2001-328900	11/27/2001	JP	C30B	29/68
0 429 270 A2	05/29/1991	EP	G03F	7/36
99/13504	03/18/1999	WO	H01L	21/68
01/15220	03/01/2001	WO	H01L	21/768
98/51838	11/19/1998	WO	C23C	16/06
00/11721	03/02/2000	WO	H01L	29/43
90/02216	03/08/1990	WO	C23C	14/34
98/06889	02/19/1998	WO	D06F	

MAILING ADDRESS OF SENDER (Please do not use customer number below):

Keith M. Tackett  
 PATTERSON & SHERIDAN, L.L.P.  
 3040 Post Oak Blvd., Suite 1500  
 Houston, TX 77056-6582

This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

SEP 13 2001

**UNITED STATES PATENT AND TRADEMARK OFFICE**  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,849,545

Page 9 of 18

APPLICATION NO. : 09/885,609

DATED : Feb. 1, 2005

INVENTOR(S) : Alfred W. MAK, Mei CHANG, Jeong Soo BYUN, Hua CHUNG, Ashok SINHA, Moris KORI

It is certified that error appears in the above-identified patent and that said Letters Patent are hereby corrected as shown below:

Item [56], References Cited, OTHER PUBLICATIONS: Please include the following references:

Hultman, et al., "Review of the thermal and mechanical stability of TiN-based thin films", Zeitschrift Fur Metallkunde, 90(10) (Oct. 1999), pp. 803-813.

Klaus, et al., "Atomic Layer Deposition of SiO<sub>2</sub> Using Catalyzed and Uncatalyzed Self-Limiting Surface Reactions", Surface Review & Letters, 6(3&4) (1999), pp. 435-448.

Yamaguchi, et al., "Atomic-layer chemical-vapor-deposition of silicon dioxide films with extremely low hydrogen content", Appl. Surf. Sci., Vol. 130-132 (1998), pp. 202-207.

George, et al., "Surface Chemistry for Atomic Layer Growth", J. Phys. Chem., Vol. 100 (1996), pp. 13121-131.

George, et al., "Atomic layer controlled deposition of SiO<sub>2</sub> and Al<sub>2</sub>O<sub>3</sub> using ABAB...binary reaction sequence chemistry", Appl. Surf. Sci., Vol. 82/83 (1994), pp. 460-467.

Wise, et al., "Diethyldioctoxysilane as a new precursor for SiO<sub>2</sub> growth on silicon", Mat. Res. Soc. Symp. Proc., Vol. 334 (1994), pp. 37-43.

Niinisto, et al., "Synthesis of oxide thin films and overlayers by atomic layer epitaxy for advanced applications", Mat. Sci. & Eng., Vol. B41 (1996), pp. 23-29.

Ritala, et al., "Perfectly conformal TiN and Al<sub>2</sub>O<sub>3</sub> films deposited by atomic layer deposition", Chemical Vapor Deposition, Vol. 5(1) (January 1999), pp. 7-9.

Min, et al., "Atomic layer deposition of TiN thin films by sequential introduction of Ti precursor and NH<sub>3</sub>", Symp.: Advanced Interconnects and Contact Materials and Processes for Future Integrated Circuits (Apr. 13-16, 1998), pp. 337-342.

Klaus, et al., "Atomic Layer Deposition of Tungsten using Sequential Surface Chemistry with a Sacrificial Stripping Reaction", Thin Solid Films 360 (2000), Pages 145 – 153, (Accepted Nov. 16, 1999).

Min, et al., "Metal-Organic Atomic-Layer Deposition of Titanium-Silicon-Nitride Films", Applied Physics Letters, American Inst. Of Physics, Vol 75(11) (Sept. 13, 1999).

Martensson, et al., "Atomic Layer Epitaxy of Copper on Tantalum", Chemical Vapor Deposition, 3(1) (Feb. 1, 1997), pp. 45-50.

MAILING ADDRESS OF SENDER (Please do not use customer number below):

Keith M. Tackett  
 PATTERSON & SHERIDAN, L.L.P.  
 3040 Post Oak Blvd., Suite 1500  
 Houston, TX 77056-6582

This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

SEP 13 2005

**UNITED STATES PATENT AND TRADEMARK OFFICE**  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,849,545

Page 10 of 18

APPLICATION NO. : 09/885,609

DATED : Feb. 1, 2005

INVENTOR(S) : Alfred W. MAK, Mei CHANG, Jeong Soo BYUN, Hua CHUNG, Ashok SINHA, Moris KORI

It is certified that error appears in the above-identified patent and that said Letters Patent are hereby corrected as shown below:

Ritala, et al. "Atomic Layer Epitaxy Growth of TiN Thin Films", J. Electrochem. Soc., 142(8) (Aug. 1995), pp. 2731-737.

Elers, et al., "NbC15 as a precursor in atomic layer epitaxy", Appl. Surf. Sci., Vol. 82/83 (1994), pp. 468-474.

Lee, "The Preparation of Titanium-Based Thin Film by CVD Using Titanium Chlorides as Precursors", Chemical Vapor Deposition, 5(2) (Mar. 1999), pp. 69-73.

Martensson, et al., "Atomic Layer Epitaxy of Copper, Growth & Selectivity in the Cu (II)-2,2,6,6-Tetramethyl-3, 5-Heptanedion ATE/H<sub>2</sub> Process", J. Electrochem. Soc., 145(8) (Aug. 1998), pp. 2926-2931.

Min, et al., "Chemical Vapor Deposition of Ti-Si-N Films with Alternating Source Supply", Mat., Res. Soc. Symp. Proc., Vol. 564 (Apr. 5, 1999), pp. 207-210

Bedair, "Atomic layer epitaxy deposition processes", J. Vac. Sci. Technol. 12(1) (Jan/Feb 1994)

Yamaga, et al., "Atomic layer epitaxy of ZnS by a new gas supplying system in a low-pressure metalorganic vapor phase epitaxy", J. of Crystal Growth 117 (1992), pp. 152-155

Elam, et al., "Nucleation and growth during tungsten atomic layer deposition on SiO<sub>2</sub> surfaces," Thin Solid Films 386 (2001) Pages 41 – 52, (Accepted Dec. 14, 2000).

Ohba, et al., "Thermal Decomposition of Methylhydrazine and Deposition Properties of CVD TiN Thin Films", Conference Proceedings, Advanced Metallization for ULSI Applications in 1993 (1994), pp. 143-149

Scheper, et al., "Low-temperature deposition of titanium nitride films from dialkylhydrazine-based precursors", Materials Science in Semiconductor Processing 2 (1999), pp. 149-157

Suzuki, et al., "A 0.2-μm contact filling by 450°C-hydrazine-reduced TiN film with low resistivity", IEDM 92-979, pp. 11.8.1 – 11.8.3

Suzuki, et al., "LPCVD-TiN Using Hydrazine and TiCl<sub>4</sub>", VMIC Conference (June 8-9, 1993), pp. 418-423

IBM Tech. Disc. Bull. "Knowledge-Based Dynamic Scheduler in Distributed Computer Control, (June 1990), pp. 80-84

IBM Tech. Disc. Bull. "Multiprocessor and Multitasking Architecture for Tool Control of the Advanced via Inspection Tools" (May 1992), pp. 190-191

MAILING ADDRESS OF SENDER (Please do not use customer number below):

Keith M. Tackett  
 PATTERSON & SHERIDAN, L.L.P.  
 3040 Post Oak Blvd., Suite 1500  
 Houston, TX 77056-6582

This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

**UNITED STATES PATENT AND TRADEMARK OFFICE**  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,849,545

Page 11 of 18

APPLICATION NO. : 09/885,609

DATED : Feb. 1, 2005

INVENTOR(S) : Alfred W. MAK, Mei CHANG, Jeong Soo BYUN, Hua CHUNG, Ashok SINHA, Moris KORI

It is certified that error appears in the above-identified patent and that said Letters Patent are hereby corrected as shown below:

McGeachin, S., "Synthesis and properties of some  $\beta$ -diketimines derived from acetylacetone, and their metal complexes", Canadian J. of Chemistry, Vol. 46 (1968), pp.1903-1912

Solanki, et al., "Atomic Layer deposition of Copper Seed Layers", Electrochemical and Solid State Letters, 3(10) (2000), pp. 479-480

NERAC.COM Retro Search: Atomic Layer Deposition of Copper, dated October 11, 2001

NERAC.COM Retro Search: Atomic Layer Deposition / Epitaxy Aluminum Oxide Plasma, dated October 2, 2001

NERAC Search abstract of "Atomic Layer deposition of Ta and Ti for Interconnect Diffusion Barriers", by Rossnagel, et al., J. Vac. Sci. & Tech., 18(4) (July 2000)

Abstracts of articles re atomic layer deposition

Abstracts of search results re atomic layer deposition, search dated January 24, 2002

Abstracts of articles re atomic layer deposition and atomic layer nucleation

Abstracts of articles re atomic layer deposition and semiconductors and copper

Abstracts of articles – atomic layer deposition

NERAC Search – Atomic Layer Deposition, search dated October 16, 2001

Bader, et al., "Integrated Processing Equipment", Solid State Technology, Cowan Pub., Vol. 33, No. 5 (May 1, 1990), pp. 149-154

Choi, et al., "The effect of annealing on resistivity of low pressure chemical vapor deposited titanium diboride", J. Appl. Phys. 69(11) (June 1, 1991), pp. 7853-7861

Choi, et al., "Stability of TiB<sub>2</sub> as a Diffusion Barrier on Silicon", J. Electrochem. Soc. 138(10) (October 1991), pp. 3062-3067

"Cluster Tools for Fabrication of Advanced devices" Jap. J. of Applied Physics, Extended Abstracts, 22nd Conference Solid State Devices and Materials (1990), pp. 849 – 852 XP000178141

MAILING ADDRESS OF SENDER (Please do not use customer number below):

Keith M. Tackett  
 PATTERSON & SHERIDAN, L.L.P.  
 3040 Post Oak Blvd., Suite 1500  
 Houston, TX 77056-6582

This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

SEP 13 2006

**UNITED STATES PATENT AND TRADEMARK OFFICE**  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,849,545

Page 12 of 18

APPLICATION NO. : 09/885,609

DATED : Feb. 1, 2005

INVENTOR(S) : Alfred W. MAK, Mei CHANG, Jeong Soo BYUN, Hua CHUNG, Ashok SINHA, Moris KORI

It is certified that error appears in the above-identified patent and that said Letters Patent are hereby corrected as shown below:

"Applications of Integrated processing", Solid State Technology, US, Cowan Pub., Vol 37, No. 12 (December 1, 1994), pp. 45-47

Kitigawa, et al., "Hydrogen-mediated low temperature epitaxy of Si in plasma-enhanced chemical vapor deposition", Applied Surface Science (2000), pp. 30-34

Lee, et al., "Pulsed nucleation for ultra-high aspect ratio tungsten plugfill", Novellus Systems, Inc. (2001), pp. 1-2.

In the Drawings

Replace all of the drawings (FIGS. 1-10, sheets 1-6) with the formal drawings (FIGS. 1-10, sheets 1-6), copies attached.

MAILING ADDRESS OF SENDER (Please do not use customer number below):

Keith M. Tackett  
 PATTERSON & SHERIDAN, L.L.P.  
 3040 Post Oak Blvd., Suite 1500  
 Houston, TX 77056-6582

This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

*If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.*

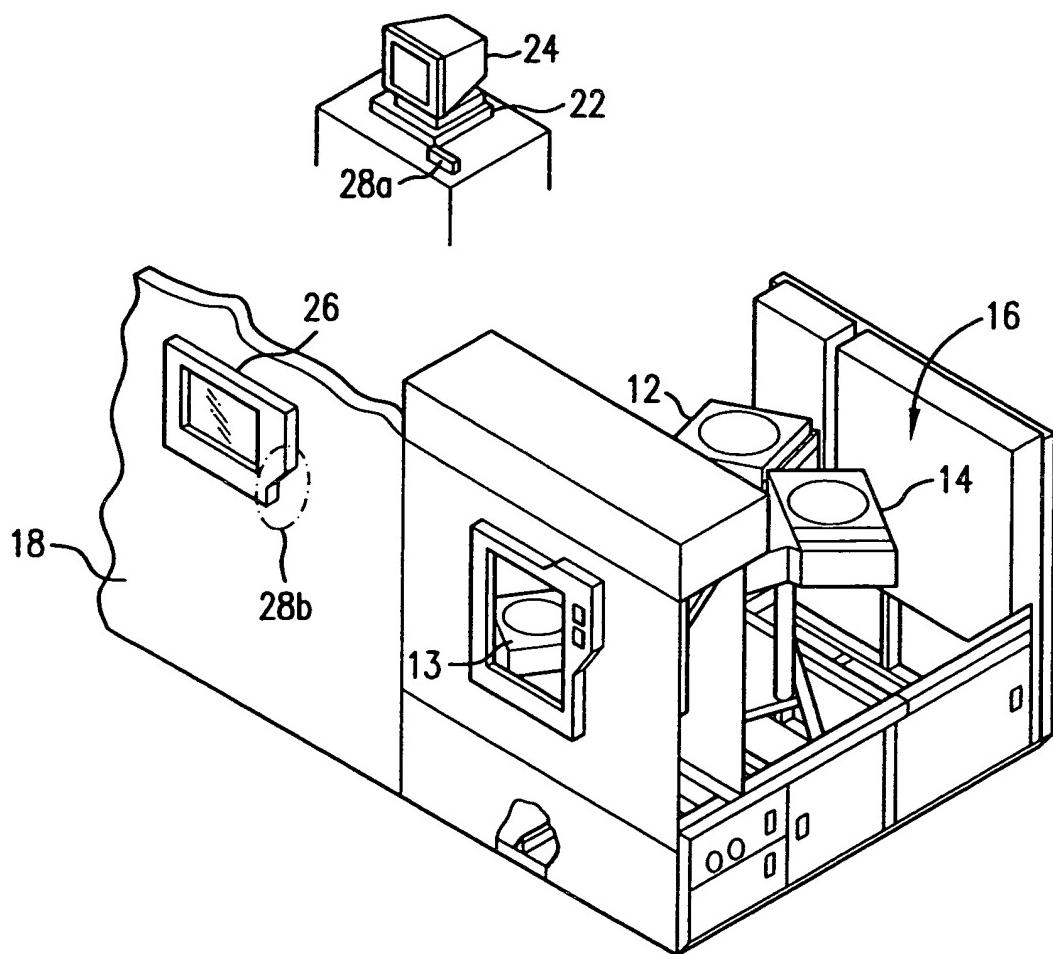
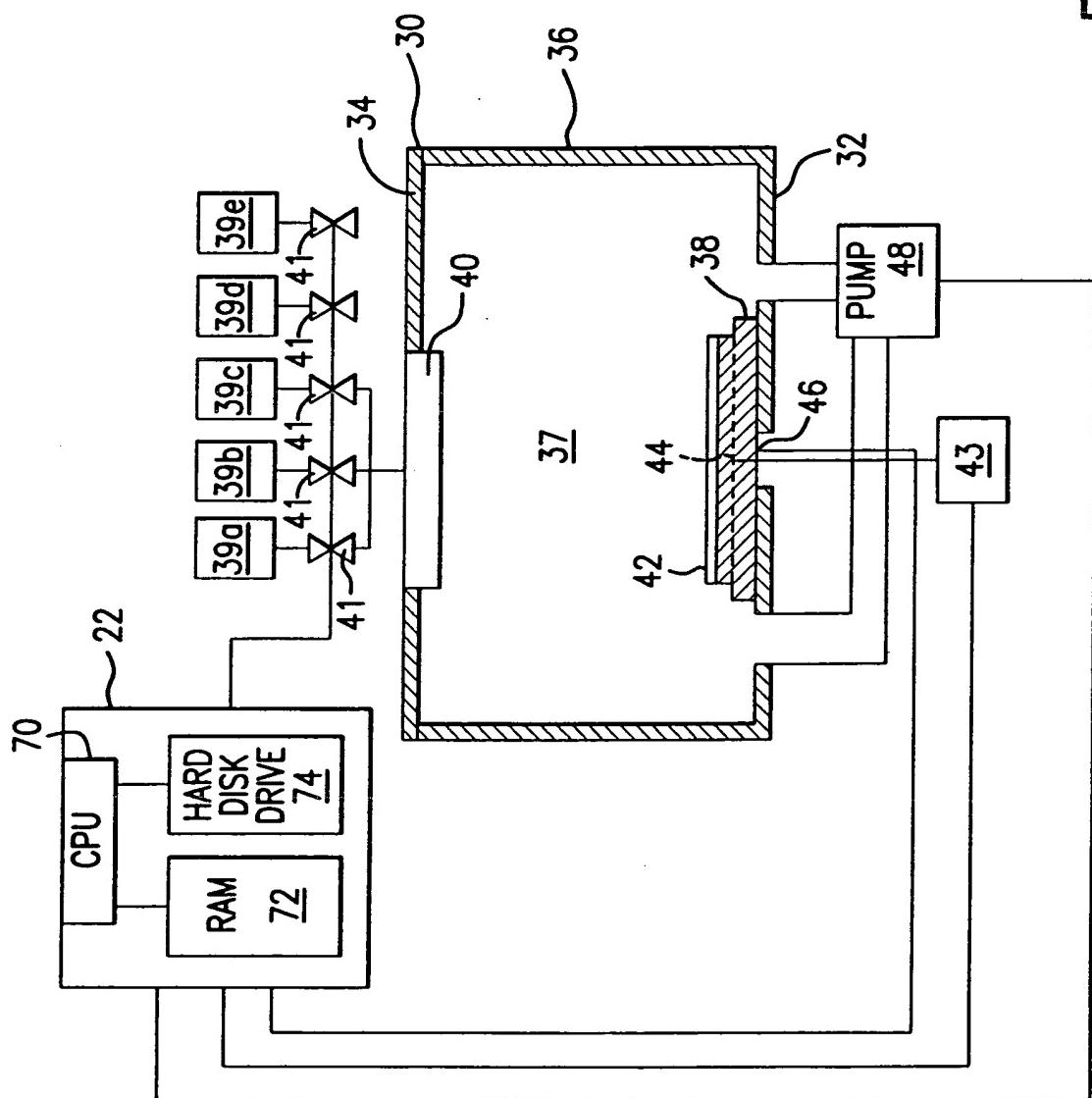


FIG. 1

FIG. 2



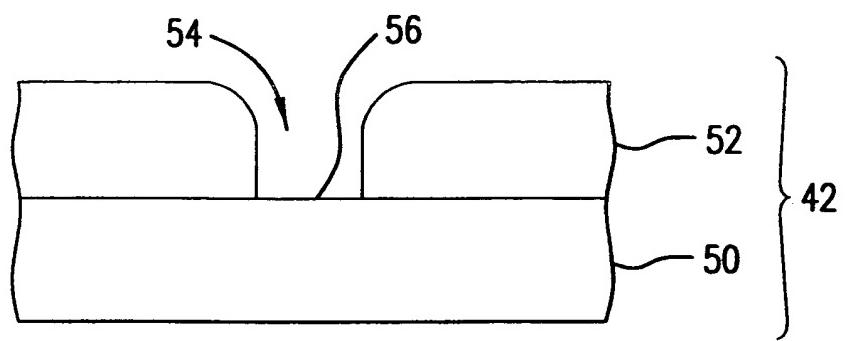


FIG. 3

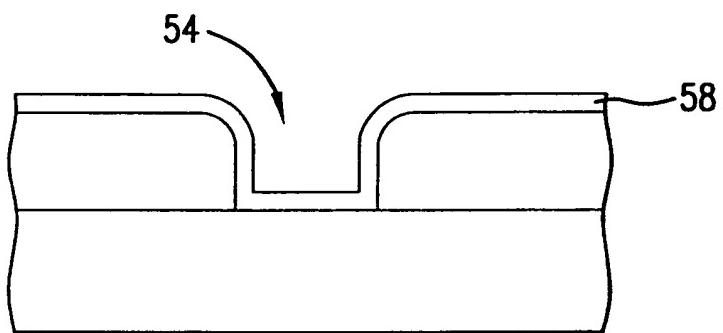


FIG. 4

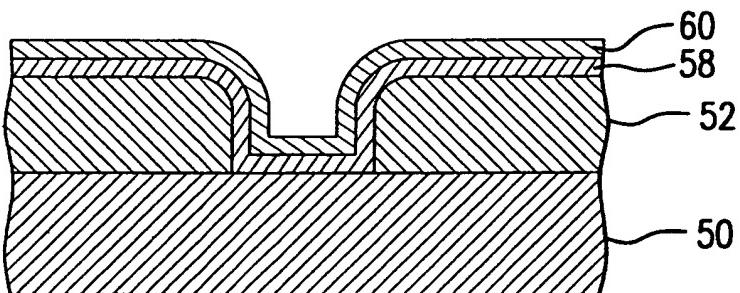


FIG. 5

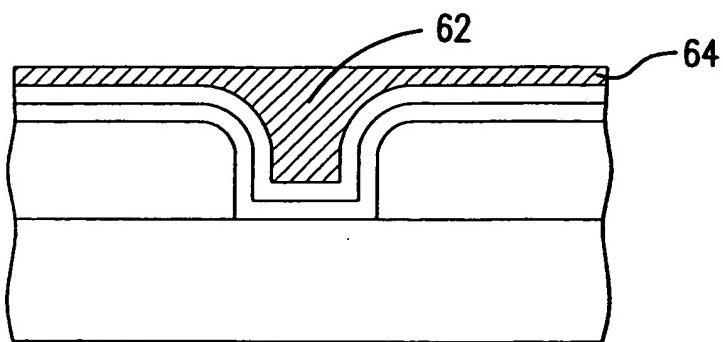


FIG. 6

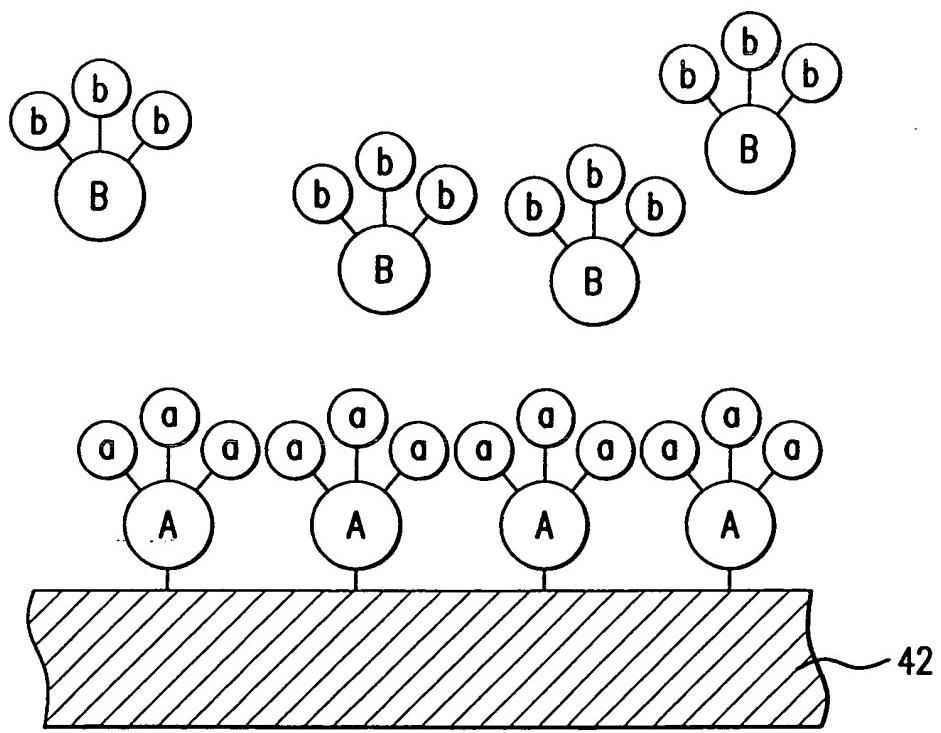


FIG. 7

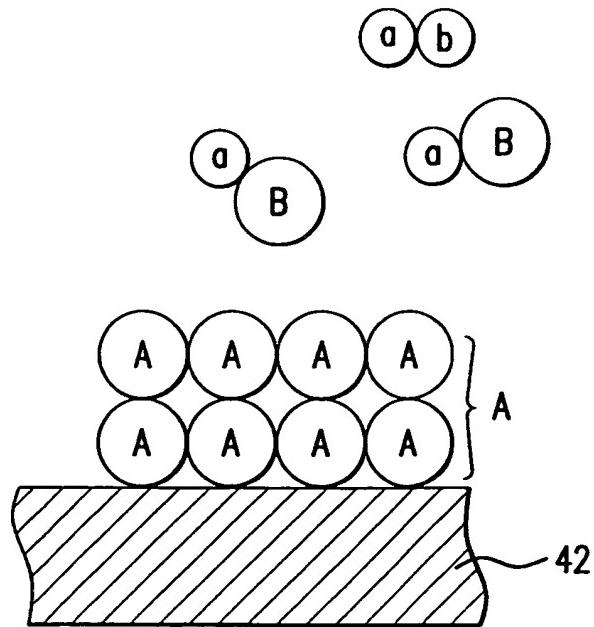


FIG. 8

13 2006

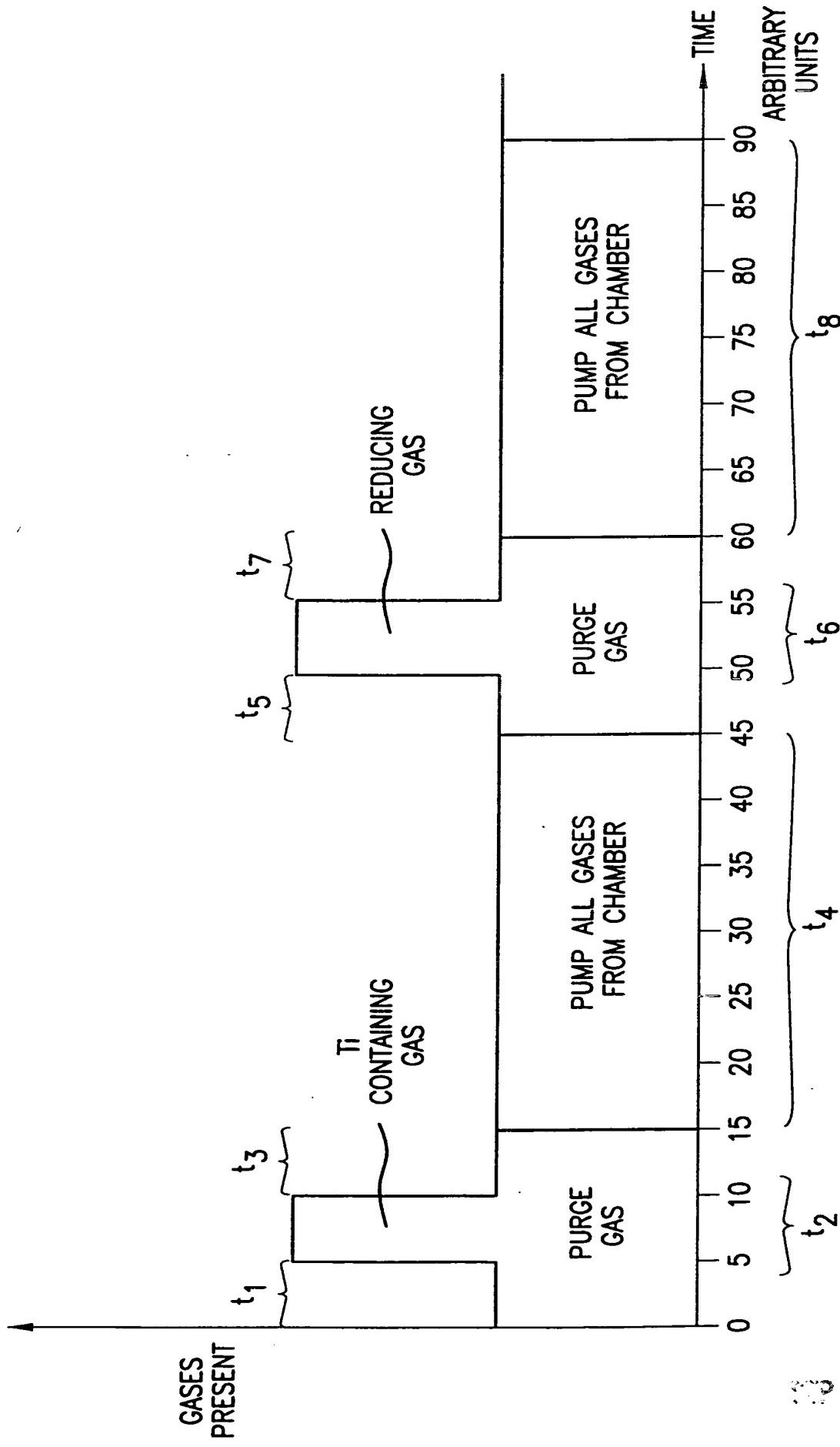


FIG. 9

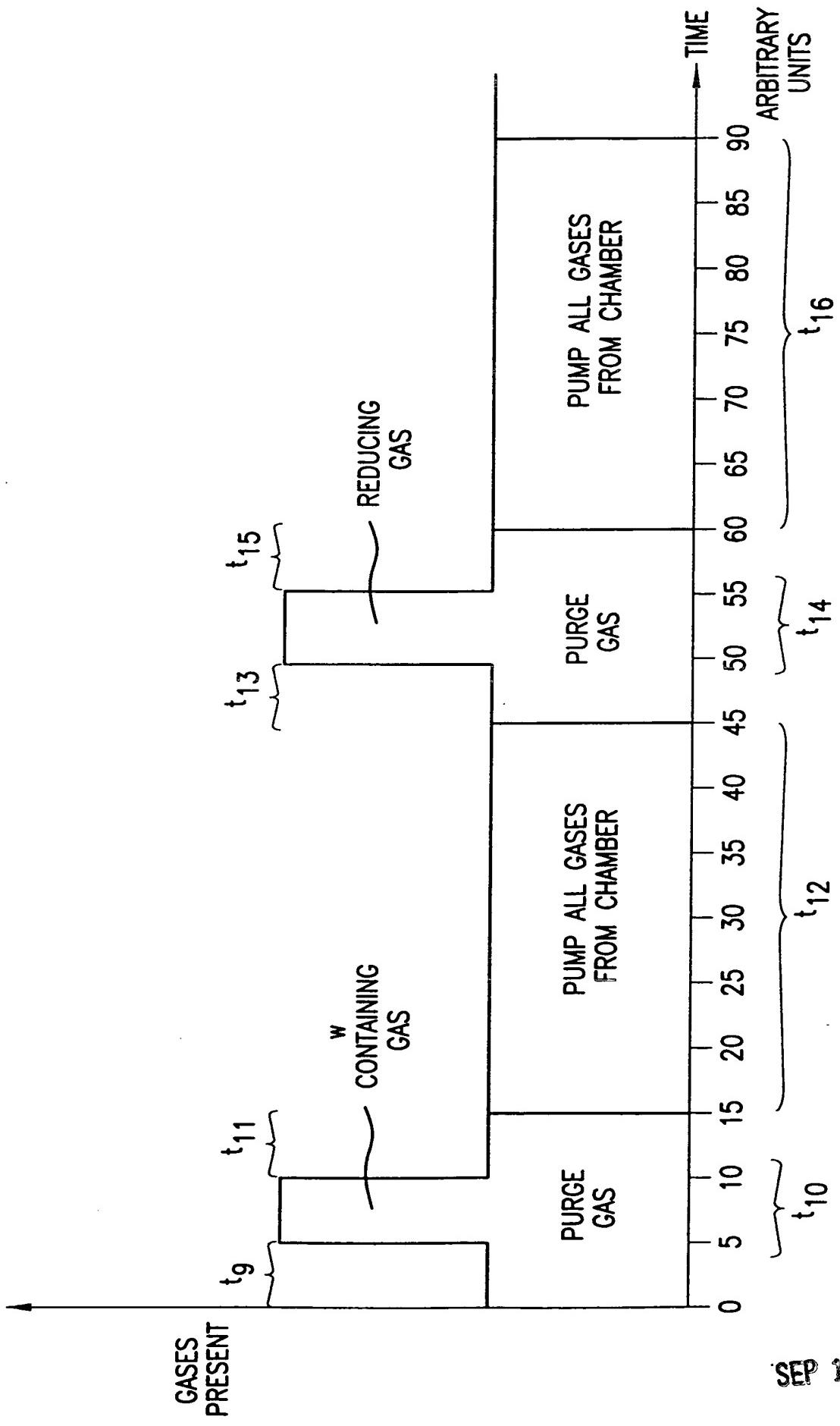


FIG. 10

SEP 13 2006



O I P E  
SEP 11 2006  
PATENT & TRADEMARK OFFICE  
UNITED STATES PATENT AND TRADEMARK OFFICE

COPY

YB  
S

UNITED STATES DEPARTMENT OF COMMERCE  
United States Patent and Trademark Office  
Address: COMMISSIONER OF PATENTS AND TRADEMARKS  
Washington, D.C. 20231  
[www.uspto.gov](http://www.uspto.gov)

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
-----------------	-------------	----------------------	---------------------	------------------

09/885,609 06/20/2001 Alfred W. Mak 5351/AMI-00-12 5337

32588 7590 03/14/2003

APPLIED MATERIALS, INC.  
2881 SCOTT BLVD. M/S 2061  
SANTA CLARA, CA 95050

EXAMINER

BERRY, RENEE R

ART UNIT	PAPER NUMBER
----------	--------------

2818

DATE MAILED: 03/14/2003

OFC 6-14-03

+3 9-14-03

Please find below and/or attached an Office communication concerning this application or proceeding.

203 552 21 61 1:00

COMPUTER ENTER  
MAR 31 2003



## Office Action Summary

	Application No. 09/885,609	Applicant(s) Mak et al.
Examiner Renee Berry	Art Unit 2818	

*-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --*

### Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136 (a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133).
- Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

### Status

1)  Responsive to communication(s) filed on \_\_\_\_\_.

2a)  This action is FINAL.      2b)  This action is non-final.

3)  Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11; 453 O.G. 213.

### Disposition of Claims

4)  Claim(s) 1-54 is/are pending in the application.

4a) Of the above, claim(s) 20-54 is/are withdrawn from consideration.

5)  Claim(s) \_\_\_\_\_ is/are allowed.

6)  Claim(s) 1-19 is/are rejected.

7)  Claim(s) \_\_\_\_\_ is/are objected to.

8)  Claims \_\_\_\_\_ are subject to restriction and/or election requirement.

### Application Papers

9)  The specification is objected to by the Examiner.

10)  The drawing(s) filed on \_\_\_\_\_ is/are a)  accepted or b)  objected to by the Examiner.

Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).

11)  The proposed drawing correction filed on \_\_\_\_\_ is: a)  approved b)  disapproved by the Examiner.

If approved, corrected drawings are required in reply to this Office action.

12)  The oath or declaration is objected to by the Examiner.

### Priority under 35 U.S.C. §§ 119 and 120

13)  Acknowledgement is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).

a)  All b)  Some\* c)  None of:

1.  Certified copies of the priority documents have been received.

2.  Certified copies of the priority documents have been received in Application No. \_\_\_\_\_.

3.  Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

\*See the attached detailed Office action for a list of the certified copies not received.

14)  Acknowledgement is made of a claim for domestic priority under 35 U.S.C. § 119(e).

a)  The translation of the foreign language provisional application has been received.

15)  Acknowledgement is made of a claim for domestic priority under 35 U.S.C. §§ 120 and/or 121.

### Attachment(s)

1)  Notice of References Cited (PTO-892)

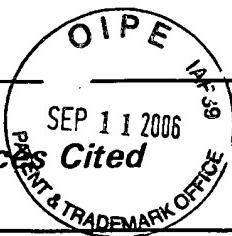
4)  Interview Summary (PTO-413) Paper No(s). \_\_\_\_\_

2)  Notice of Draftsperson's Patent Drawing Review (PTO-948)

5)  Notice of Informal Patent Application (PTO-152)

3)  Information Disclosure Statement(s) (PTO-1449) Paper No(s). \_\_\_\_\_

6)  Other: \_\_\_\_\_



## Notice of References Cited

Application/Control No.  
09/885,609

Applicant(s)/Patent Under Reexam  
Mak et al.

Examiner  
Renee Berry

Art Unit  
2818

Page 1 of 1

### U.S. PATENT DOCUMENTS

	Document Number Country Code-Number-Kind Code	Date MM-YYYY <sup>1</sup>	Name	Classification <sup>2</sup>	
A	5,393,565	6/1993	Suzuki et al.	427	255.2
B	5,942,799	11/1997	Danek et al.	257	751
C	6,495,449	5/2000	Nguyen	438	627
D					
E					
F					
G					
H					
I					
J					
K					
L					
M					

### FOREIGN PATENT DOCUMENTS

	Document Number Country Code-Number-Kind Code	Date MM-YYYY <sup>1</sup>	Country	Name	Classification <sup>2</sup>	
N						
O						
P						
Q						
R						
S						
T						

### NON-PATENT DOCUMENTS

	Include, as applicable: Author, Title, Date, Publisher, Edition or Volume, Pertinent Pages
U	
V	
W	
X	

\* A copy of this reference is not being furnished with this Office action. See MPEP § 707.05(a).

<sup>1</sup> Dates in MM-YYYY format are publication dates.

<sup>2</sup> Classifications may be U.S. or foreign.

K SEP 11 2006  
UNITED STATES PATENT AND TRADEMARK OFFICEO I P E  
T A K S  
U N I T E D S T A T E S P A T E N T A N D T R A D E M A R K O F F I C E8/F  
8/PB>JC  
11-2  
UNITED STATES DEPARTMENT OF COMMERCE  
United States Patent and Trademark Office  
Address: COMMISSIONER FOR PATENTS  
P.O. Box 1450  
Alexandria, Virginia 22313-1450  
[www.uspto.gov](http://www.uspto.gov)

## NOTICE OF ALLOWANCE AND FEE(S) DUE

32588 7590 08/02/2004

APPLIED MATERIALS, INC.  
2881 SCOTT BLVD. M/S 2061  
SANTA CLARA, CA 95050

EXAMINER

BERRY, RENEE R

ART UNIT PAPER NUMBER

2818

DATE MAILED: 08/02/2004

COMPUTER ENTERED  
AUG 17 2004  
RECD AUG 18 2004

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/885,609	06/20/2001	Alfred W. Mak	5351/AMI-00-12	5337

TITLE OF INVENTION: SYSTEM AND METHOD TO FORM A COMPOSITE FILM STACK UTILIZING SEQUENTIAL DEPOSITION TECHNIQUES

APPLN. TYPE	SMALL ENTITY	ISSUE FEE	PUBLICATION FEE	TOTAL FEE(S) DUE	DATE DUE
nonprovisional	NO	\$1330	\$300	\$1630	11/02/2004

THE APPLICATION IDENTIFIED ABOVE HAS BEEN EXAMINED AND IS ALLOWED FOR ISSUANCE AS A PATENT. PROSECUTION ON THE MERITS IS CLOSED. THIS NOTICE OF ALLOWANCE IS NOT A GRANT OF PATENT RIGHT. THIS APPLICATION IS SUBJECT TO WITHDRAWAL FROM ISSUE AT THE INITIATIVE OF THE OFFICE OR UPON PETITION BY THE APPLICANT. SEE 37 CFR 1.313 AND MPEP 1308.

THE ISSUE FEE AND PUBLICATION FEE (IF REQUIRED) MUST BE PAID WITHIN THREE MONTHS FROM THE MAILING DATE OF THIS NOTICE OR THIS APPLICATION SHALL BE REGARDED AS ABANDONED. THE STATUTORY PERIOD CANNOT BE EXTENDED. SEE 35 U.S.C. 151. THE ISSUE FEE DUE INDICATED ABOVE REFLECTS A CREDIT FOR ANY PREVIOUSLY PAID ISSUE FEE APPLIED IN THIS APPLICATION. THE PTOL-85B (O AN EQUIVALENT) MUST BE RETURNED WITHIN THIS PERIOD EVEN IF NO FEE IS DUE OR THE APPLICATION WILL BE REGARDED AS ABANDONED.

## HOW TO REPLY TO THIS NOTICE:

I. Review the SMALL ENTITY status shown above.

If the SMALL ENTITY is shown as YES, verify your current SMALL ENTITY status:

A. If the status is the same, pay the TOTAL FEE(S) DUE shown above.

B. If the status above is to be removed, check box 5b on Part B - Fee(s) Transmittal and pay the PUBLICATION FEE (if required) and twice the amount of the ISSUE FEE shown above, or

If the SMALL ENTITY is shown as NO:

A. Pay TOTAL FEE(S) DUE shown above, or

B. If applicant claimed SMALL ENTITY status before, or is now claiming SMALL ENTITY status, check box 5a on Part B - Fee Transmittal and pay the PUBLICATION FEE (if required) and twice the ISSUE FEE shown above.

II. PART B - FEE(S) TRANSMITTAL should be completed and returned to the United States Patent and Trademark Office (USPTO) with your ISSUE FEE and PUBLICATION FEE (if required). Even if the fee(s) have already been paid, Part B - Fee(s) Transmittal should be completed and returned. If you are charging the fee(s) to your deposit account, section "4b" of Part B - Fee(s) Transmittal should be completed and an extra copy of the form should be submitted.

III. All communications regarding this application must give the application number. Please direct all communications prior to issuance to Mail Stop ISSUE FEE unless advised to the contrary.

IMPORTANT REMINDER: Utility patents issuing on applications filed on or after Dec. 12, 1980 may require payment of maintenance fees. It is patentee's responsibility to ensure timely payment of maintenance fees when due.



## Notice of Allowability

	Application No.	Applicant(s)
	09/885,609	MAK ET AL
	Examiner	Art Unit
	Renee R Berry	2818

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address--

All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.

1.  This communication is responsive to 2/26/04.
  2.  The allowed claim(s) is/are 1-19 and 26-32.
  3.  The drawings filed on 20 June 2001 are accepted by the Examiner.
  4.  Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
    - a)  All
    - b)  Some\*
    - c)  None
 of the:
    1.  Certified copies of the priority documents have been received.
    2.  Certified copies of the priority documents have been received in Application No. \_\_\_\_\_.
    3.  Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).
- \* Certified copies not received: \_\_\_\_\_.
5.  Acknowledgment is made of a claim for domestic priority under 35 U.S.C. § 119(e) (to a provisional application) since a specific reference was included in the first sentence of the specification or in an Application Data Sheet. 37 CFR 1.78.
    - (a)  The translation of the foreign language provisional application has been received.
  6.  Acknowledgment is made of a claim for domestic priority under 35 U.S.C. §§ 120 and/or 121 since a specific reference was included in the first sentence of the specification or in an Application Data Sheet. 37 CFR 1.78.
- Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application. THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.
7.  A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.
  8.  CORRECTED DRAWINGS (as "replacement sheets") must be submitted.
    - (a)  including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached
      - 1)  hereto or 2)  to Paper No. \_\_\_\_\_.
    - (b)  including changes required by the proposed drawing correction filed \_\_\_\_\_, which has been approved by the Examiner.
    - (c)  including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No. \_\_\_\_\_.

Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the margin according to 37 CFR 1.121(d).

9.  DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.

### Attachment(s)

- 1  Notice of References Cited (PTO-892)
- 2  Notice of Draftsperson's Patent Drawing Review (PTO-948)
- 3  Information Disclosure Statements (PTO-1449 or PTO/SB/08),  
Paper No. \_\_\_\_\_
- 4  Examiner's Comment Regarding Requirement for Deposit  
of Biological Material
- 5  Notice of Informal Patent Application (PTO-152)
- 6  Interview Summary (PTO-413), Paper No. \_\_\_\_\_
- 7  Examiner's Amendment/Comment
- 8  Examiner's Statement of Reasons for Allowance
- 9  Other

  
 David Neims  
 Supervisory Patent Examiner  
 Technology Center 2800

Please type a plus sign (+) inside this box → +

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number.

SEP 11 2006

PTO/SB/08a (08-03)

Approved for use through 07/31/2006. OMB 0651-0031  
U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

Substitute for form 1449A/PTO

TEB 26 2004

Application Number	09/885,609
Filing Date	June 20, 2001
First Named Inventor	Alfred W. Mak et al.
Group Art Unit	2818
Examiner Name	Berry, Renee R.
Attorney Docket Number	AMAT/5351/CPI/L/B/PJS
Sheet	1
of	2
Submission Date	February 26, 2004

## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

### U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)			
AM	A1	US-5,804,488	09-08-1998	Shih et al.	
AM	A2	US-6,218,298 B1	04-17-2001	Hoinkis	
AM	A3	US-6,335,280 B1	01-01-2002	Van der Jeugd	
AM	A4	US-6,551,929 B1	04-22-2003	Kori et al.	
AM	A5	US-6,599,572 B2	07-29-2003	Saanila et al.	
AM	A6	US-6,607,976 B2	08-19-2003	Chen et al.	
AM	A7	US-6,632,279 B1	10-14-2003	Ritala et al.	
AM	A8	US-6,686,271 B2	02-03-2004	Raaijmakers et al.	
AM	A9	US-2002/0086111 A1	07-04-2002	Byun et al.	
AM	A10	US-2002/0121241 A1	09-05-2002	Nguyen et al.	
AM	A11	US-2002/0121342 A1	09-05-2002	Nguyen et al.	
AM	A12	US-2003/0013300 A1	01-16-2003	Byun	
AM	A13	US-2003/0054631 A1	03-20-2003	Raaijmakers et al.	
AM	A14	US-2003/0089308 A1	05-15-2003	Raaijmakers	
AM	A15	US-2003/0101927 A1	06-05-2003	Raaijmakers	
AM	A16	US-2003/0104126 A1	06-05-2003	Fang et al.	
AM	A17	US-2003/0129826 A1	07-10-2003	Werkhoven et al.	
AM	A18	US-2003/0134508 A1	07-17-2003	Raaijmakers et al.	

### FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
		Number-Kind Code <sup>2</sup> (if known)				
AM	B1	WO 02/01628 A2	01-03-2002	Byun et al.		
AM	B2	WO 02/45871 A1	06-13-2002	Chiang et al		
	B3					
	B4					

Examiner

Date Considered

7-10-04

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. 1 Applicant's unique citation designation number (optional). 2 See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). 4 For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document, & kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. 6 Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450. If you need assistance in completing the form, call 1-800-PTO-9199 (1-800-786-9199) and select option 2.



PATENT  
Atty. Dkt. APPM/5351/CPI/L/B/PJS

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:  
Mak, et al.

ଶ୍ରୀ କମଳାଚାର୍ଯ୍ୟ

Group Art Unit: 2812

Serial No.: 09/885,609

卷之三

Confirmation No.: 5337

卷之三

Filed: June 20, 2001

200

**For:** System and Method to  
Form a Composite Film  
Stack Utilizing Sequential  
Deposition Techniques

卷之三

Assistant Commissioner for Patents  
Washington, D.C. 20231

**CERTIFICATE OF MAILING**  
**37 CFR 1.8**

3/2/02

Signature

Dear Sir:

## **SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

The Applicants, and the Attorney who signs below on the basis of the information supplied by the inventor and the information in his file, submit herewith patents, publications, or other information of which they are aware, which may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

While the information submitted in this Supplemental Information Disclosure Statement may be material pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication, or other information referred to therein is prior art for this invention unless specifically designated as such.

In accordance with 37 CFR § 1.97, this Supplemental Information Disclosure Statement is not to be construed as a representation that a search has been made or that no other possibly material information as defined under 37 CFR § 1.56(a) exists.

The patents and/or publications submitted herewith are set forth on the attached Form PTO-1449.

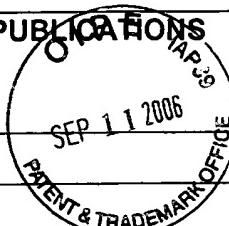
If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/APPM/5351/BTP.

Respectfully submitted,

*Keith M. Tackett*

Keith M. Tackett  
Registration No. 32,008  
MOSER, PATTERSON & SHERIDAN, L.L.P.  
3040 Post Oak Blvd., Suite 1500  
Houston, TX 77056  
Telephone: (713) 623-4844  
Facsimile: (713) 623-4846  
Attorney for Applicant(s)

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. APPM/5351	Serial No. 09/885,609
<b>SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>		Applicant Mak, et al.	Confirmation No.: 5337
(Use several sheets if necessary)		Filing Date June 20, 2001	Group 2812
	Examiner      Berry		

**U.S. Patent Documents**

*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A1	4,813,846	03/21/89	Helms	414	744.1	04/29/87
	A2	4,917,556	04/17/90	Stark et al.	414	217	05/26/89
	A3	4,951,601	08/28/90	Maydan, et al.	118	719	06/23/89
	A4	5,000,113	03/19/91	Wang et al.	118	723	12/19/86
	A5	5,028,565	07/02/1991	Chang, et al.	437	192	08/25/1989
	A6	5,173,474	12/22/1992	Connell, et al.	505	1	03/11/1991
	A7	5,186,718	02/16/93	Tepman et al.	29	25.01	04/15/91
	A8	5,205,077	04/27/93	Wittstock	51	165 R	08/28/91
	A9	5,234,561	08/10/93	Randhawa et al.	204	192.38	08/25/88
	A10	5,259,881	11/09/93	Edwards, et al.	118	719	05/17/91
	A11	5,286,296	02/15/94	Sato et al.	118	719	01/09/92
	A12	5,580,380	12/03/1996	Liu, et al.	117	86	01/30/1995
	A13	5,609,689	03/11/97	Kato et al.	118	719	06/03/96
	A14	5,667,592	09/16/97	Boitnott et al.	118	719	04/16/96
	A15	5,674,786	10/07/97	Turner et al.	437	225	06/05/95
	A16	5,695,564	12/09/97	Imahashi	118	719	08/03/95
	A17	5,730,801	03/24/98	Tepman et al.	118	719	08/23/94
	A18	5,788,447	08/04/98	Yonemitsu et al.	414	217	08/05/96
	A19	5,788,799	08/04/98	Steger, et al.	156	345	06/11/96
	A20	5,801,634	09/01/98	Young et al.	340	635	09/08/97
	A21	5,856,219	01/05/99	Naito et al.	438	241	08/18/97
	A22	5,866,213	02/02/99	Foster et al.	427	573	07/19/97
	A23	5,866,795	02/02/99	Wang et al.	73	1.36	03/17/97
	A24	5,882,165	03/16/99	Maydan et al.	414	217	09/10/97
	A25	5,882,413	03/16/99	Beaulieu et al.	118	719	07/11/97
	A26	5,928,389	07/27/99	Jevtic	29	25.01	10/21/96

Examiner

Date Considered

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office				Docket No. APPM/5351	Serial No. 09/885,609	
(PTO Form 1449 modified)						
<b>SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>				Applicant Mak, et al.	Confirmation No.: 5337	
(Use several sheets if necessary)				Filing Date June 20, 2001	Group	
	Examiner Berry				2812	

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B1	58-098917	06/13/1983	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B2	58-100419	06/15/1983	JP	H01L	21/20	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B3	61-035847	02/20/1986	JP	B01J	19/08	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B4	61-210623	09/18/1986	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B5	62-069508	03/30/1987	JP	H01L	21/203	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B6	62-141717	06/25/1987	JP	H01L	21/203	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B7	62-167297	07/23/1987	JP	C30B	29/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B8	62-171999	07/28/1987	JP	C30B	29/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B9	62-232919	10/13/1987	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B10	63-062313	03/18/1988	JP	H01L	21/203	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B11	63-085098	04/15/1988	JP	C30B	21/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B12	63-090833	04/21/1988	JP	H01L	21/365	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B13	63-222420	09/16/1988	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B14	63-222421	09/16/1988	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B15	63-227007	09/21/1988	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B16	63-252420	10/19/1988	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B17	63-266814	11/02/1988	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B18	64-009895	01/13/1989	JP	C30B	29/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B19	64-009896	01/13/1989	JP	C30B	29/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B20	64-009897	01/13/1989	JP	C30B	29/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B21	64-037832	02/08/1989	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B22	64-082615	03/28/1989	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B23	64-082617	03/28/1989	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B 24	64-082671	03/28/1989	JP	H01L	29/78	<input checked="" type="checkbox"/>	<input type="checkbox"/>

Examiner

Date Considered

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. APPM/5351	Serial No. 09/885,609
SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT		Applicant Mak, et al.	Confirmation No.: 5337
(Use several sheets if necessary)		Filing Date June 20, 2001	Group 2812
	Examiner      Berry		

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B25	64-082676	03/28/1989	JP	H01L	29/80	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B26	64-090524	04/07/1989	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B27	01-103982	04/21/1989	JP	C30B	23/08	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B28	01-103996	04/21/1989	JP	C30B	29/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B29	01-117017	05/09/1989	JP	H01L	21/203	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B30	01-143221	06/05/1989	JP	H01L	21/314	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B31	01-143233	06/05/1989	JP	H01L	21/76	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B32	01-154511	06/16/1989	JP	H01L	21/20	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B33	01-236657	09/21/1989	JP	H01L	29/80	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B34	01-245512	09/29/1989	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B35	01-264218	10/20/1989	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B36	01-270593	10/27/1989	JP	C30B	25/02	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B37	01-272108	10/31/1989	JP	H01L	21/203	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B38	01-290221	11/22/1989	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B39	01-290222	11/22/1989	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B40	01-296673	11/30/1989	JP	H01L	29/88	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B41	01-303770	12/07/1989	JP	H01L	39/24	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B42	01-305894	12/11/1989	JP	C30B	23/08	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B43	01-313927	12/19/1989	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B44	02-012814	01/17/1990	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B45	02-014513	01/18/1990	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B46	02-017634	01/22/1990	JP	H01L	21/225	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B47	02-063115	03/02/1990	JP	H01L	21/20	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B48	02-074029	03/14/1990	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>

Examiner

Date Considered

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. APPM/5351	Serial No. 09/885,609
<b>SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>		Applicant Mak, et al.	Confirmation No.: 5337
(Use several sheets if necessary)		Filing Date June 20, 2001	Group 2812
	Examiner    Berry		

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B49	02-074587	03/14/1990	JP	C30B	23/08	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B50	02-106822	04/18/1990	JP	H01B	13/00	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B51	02-129913	05/18/1990	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B52	02-162717	06/22/1990	JP	H01L	21/20	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B53	02-172895	07/04/1990	JP	C30B	29/36	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B54	02-196092	08/02/1990	JP	C30B	25/14	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B55	02-203517	08/13/1990	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B56	02-230690	09/13/1990	JP	H05B	33/10	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B57	02-230722	09/13/1990	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B58	02-246161	10/01/1990	JP	H01L	29/784	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B59	02-264491	10/29/1990	JP	H01S	3/18	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B60	02-283084	11/20/1990	JP	H01S	3/18	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B61	02-304916	12/18/1990	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B62	03-019211	01/28/1991	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B63	03-022569	01/30/1991	JP	H01L	29/804	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B64	03-023294	01/31/1991	JP	C30B	25/18	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B65	03-023299	01/31/1991	JP	C30B	29/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B66	03-044967	02/26/1991	JP	H01L	29/48	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B67	03-070124	03/26/1991	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B68	03-185716	08/13/1991	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B69	03-208885	09/12/1991	JP	C30B	23/02	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B70	03-234025	10/18/1991	JP	H01L	21/318	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B71	03-286522	12/17/1991	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B72	04-031391	02/03/1992	JP	C30B	23/08	<input checked="" type="checkbox"/>	<input type="checkbox"/>

Examiner

Date Considered

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)			Docket No. APPM/5351	Serial No. 09/885,609
<b>SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>			Applicant Mak, et al.	Confirmation No.: 5337
(Use several sheets if necessary)			Filing Date June 20, 2001	Group 2812
Examiner    Berry				

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B73	04-031396	02/03/1992	JP	C30B	25/14	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B74	04-100292	04/02/1992	JP	H01S	3/18	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B75	04-111418	04/13/1992	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B76	04-132214	05/06/1992	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B77	04-132681	05/06/1992	JP	C30B	25/14	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B78	04/151822	05/25/1992	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B79	04-162418	06/05/1992	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B80	04-175299	06/23/1992	JP	C30B	29/68	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B81	04-186824	07/03/1992	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B82	04-212411	08/04/1992	JP	H01L	21/203	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B83	04-260696	09/16/1992	JP	C30B	29/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B84	04-273120	09/29/1992	JP	H01L	21/20	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B85	04-285167	10/09/1992	JP	C23C	14/54	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B86	04-291916	10/16/1992	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B87	04-325500	11/13/1992	JP	C30B	33/00	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B88	04-328874	11/17/1992	JP	H01L	29/804	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B89	05-029228	02/05/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B90	05-047665	02/26/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B91	05-047666	02/26/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B92	05-047668	02/26/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B93	05-074717	03/26/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B94	05-074724	03/26/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B95	05-102189	04/23/1993	JP	H01L	21/336	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B96	05-160152	06/25/1993	JP	H01L	21/336	<input checked="" type="checkbox"/>	<input type="checkbox"/>

Examiner

Date Considered

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. APPM/5351	Serial No. 09/885,609
<b>SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>		Applicant Mak, et al.	Confirmation No.: 5337
(Use several sheets if necessary)		Filing Date June 20, 2001	Group 2812
	Examiner      Berry		

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B97	05-175143	07/13/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B98	05-175145	07/13/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B99	05-182906	07/23/1993	JP	H01L	21/20	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B100	05-186295	07/27/1993	JP	C30B	25/02	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B101	05-206036	08/13/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B102	05-234899	09/10/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B103	05-235047	09/10/1993	JP	H01L	21/338	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B104	05-251339	09/28/1993	JP	H01L	21/20	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B105	05-270997	10/19/1993	JP	C30B	29/68	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B106	05-283336	10/29/1993	JP	H01L	21/20	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B107	05-291152	11/05/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B108	05-304334	11/16/1993	JP	H01L	3/18	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B109	05-343327	12/24/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B110	05-343685	12/24/1993	JP	H01L	29/784	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B111	06-045606	02/18/1994	JP	H01L	29/784	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B112	06-132236	05/13/1994	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B113	06-177381	06/24/1994	JP	H01L	29/784	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B114	06-196809	07/15/1994	JP	H01S	3/18	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B115	06-222388	08/12/1994	JP	G02F	1/136	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B116	06-224138	08/12/1994	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B117	06-230421	08/19/1994	JP	G02F	1/136	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B118	06-252057	09/09/1994	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B119	07-070752	03/14/1995	JP	C23C	16/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B120	07-086269	03/13/1995	JP	H01L	21/314	<input checked="" type="checkbox"/>	<input type="checkbox"/>

Examiner

Date Considered

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. APPM/5351	Serial No. 09/885,609
<b>SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>		Applicant Mak, et al.	Confirmation No.: 5337
(Use several sheets if necessary)		Filing Date June 20, 2001	Group 2812
	Examiner    Berry		

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B121	07-086269	03/13/1995	JP	H01L	21/314	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B122	08-181076	07/12/1996	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B123	08-245291	09/24/1996	JP	C30B	25/14	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B124	09-260786	10/03/1997	JP	H01S	3/18	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B125	09-293681	11/11/1997	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B126	10-188840	07/21/1998	JP	H01J	29/18	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B127	10-190128	07/21/1998	JP	H01S	3/18	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B128	10-308283	11/17/1998	JP	H05B	33/22	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B129	11-269652	10/05/1999	JP	C23C	16/44	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B130	2000-031387	01/28/2000	JP	H01L	27/04	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B131	2000-058777	02/25/2000	JP	H01L	27/108	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B132	2000-068072	03/03/2000	JP	H05B	33/22	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B133	2000-087029	03/28/2000	JP	C09K	11/08	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B134	2000-138094	05/16/2000	JP	H05B	33/10	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B135	2000-218445	08/08/2000	JP	B23P	6/00	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B136	2000-319772	11/21/2000	JP	C23C	14/24	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B137	2000-319772	03/28/2000	JP	C23C	16/00	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B138	2000-340883	12/08/2000	JP	H01S	5/125	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B139	2000-353666	12/19/2000	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B140	2001-020075	01/23/2001	JP	C23C	16/44	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B141	2001-152339	06/05/2001	JP	C23C	16/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B142	2001-172767	06/26/2001	JP	C23C	16/40	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B143	2001-189312	07/10/2001	JP	H01L	21/316	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B144	2001-217206	08/10/2001	JP	H01L	21/285	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B145	2001-220287	08/14/2001	JP	C30B	25/02	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B146	2001-220294	08/14/2001	JP	C30B	29/20	<input checked="" type="checkbox"/>	<input type="checkbox"/>

Examiner	Date Considered
----------	-----------------

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)	Docket No. APPM/5351	Serial No. 09/885,609
<b>SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>	Applicant Mak, et al.	Confirmation No.: 5337
(Use several sheets if necessary)	Filing Date June 20, 2001	Group 2812
Examiner      Berry		

## **Foreign Patent Documents**

**Examiner**

### Date Considered

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. APPM/5351	Serial No. 09/885,609
<b>SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>		Applicant Mak, et al.	Confirmation No.: 5337
(Use several sheets if necessary)		Filing Date June 20, 2001	Group 2812
<b>OTHER ART</b>			
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.	
	C1	Ohba, et al., "Thermal Decomposition of Methylhydrazine and Deposition Properties of CVD TiN Thin Films", Conference Proceedings, Advanced Metallization for ULSI Applications in 1993 (1994), pp. 143-149	
	C2	Scheper, et al., "Low-temperature deposition of titanium nitride films from dialkylhydrazine-based precursors", Materials Science in Semiconductor Processing 2 (1999), pp. 149-157	
	C3	Suzuki, et al., "A 0.2-µm contact filing by 450°C-hydrazine-reduced TiN film with low resistivity", IEDM 92-979, pp. 11.8.1 – 11.8.3	
	C4	Suzuki, et al., "LPCVD-TiN Using Hydrazine and TiCl <sub>4</sub> ", VMIC Conference (June 8-9, 1993), pp. 418-423	
	C5	IBM Tech. Disc. Bull. "Knowledge-Based Dynamic Scheduler in Distributed Computer Control, (June 1990), pp. 80-84	
	C6	IBM Tech. Disc. Bull. "Multiprocessor and Multitasking Architecture for Tool Control of the Advanced via Inspection Tools" (May 1992), pp. 190-191	
	C7	McGeachin, S., "Synthesis and properties of some β-diketimines derived from acetylacetone, and their metal complexes", Canadian J. of Chemistry, Vol. 46 (1968), pp.1903-1912	
	C8	Solanki, et al., "Atomic Layer deposition of Copper Seed Layers", Electrochemical and Solid State Letters, 3(10) (2000), pp. 479-480	
	C9	NERAC.COM Retro Search: Atomic Layer Deposition of Copper, dated October 11, 2001	
	C10	NERAC.COM Retro Search: Atomic Layer Deposition / Epitaxy Aluminum Oxide Plasma, dated October 2, 2001	
	C11	NERAC Search abstract of "Atomic Layer deposition of Ta and Ti for Interconnect Diffusion Barriers", by Rossnagel, et al., J. Vac. Sci. & Tech., 18(4) (July 2000)	
	C12	Abstracts of articles re atomic layer deposition	
	C13	Abstracts of search results re atomic layer deposition, search dated January 24, 2002	
	C14	Abstracts of articles re atomic layer deposition and atomic layer nucleation	
	C15	Abstracts of articles re atomic layer deposition and semiconductors and copper	
Examiner		Date Considered	
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.			

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. APPM/5351	Serial No. 09/885,609																																																																				
<b>SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>		Applicant Mak, et al.	Confirmation No.: 5337																																																																				
(Use several sheets if necessary)		Filing Date June 20, 2001	Group 2812																																																																				
<p><b>OTHER ART</b></p> <table border="1"> <tr> <td>*Examiner Initial</td> <td></td> <td colspan="2">Including Author, Title, Date, Pertinent Pages, Etc.</td> </tr> <tr> <td></td> <td>C16</td> <td colspan="2">Abstracts of articles – atomic layer deposition</td> </tr> <tr> <td></td> <td>C17</td> <td colspan="2">NERAC Search – Atomic Layer Deposition, search dated October 16, 2001</td> </tr> <tr> <td></td> <td>C18</td> <td colspan="2">Bader, et al., "Integrated Processing Equipment", Solid State Technology, Cowan Pub., Vol. 33, No. 5 (May 1, 1990), pp. 149-154</td> </tr> <tr> <td></td> <td>C19</td> <td colspan="2">Choi, et al., "The effect of annealing on resistivity of low pressure chemical vapor deposited titanium diboride", J. Appl. Phys. 69(11) (June 1, 1991), pp. 7853-7861</td> </tr> <tr> <td></td> <td>C20</td> <td colspan="2">Choi, et al., "Stability of TiB<sub>2</sub> as a Diffusion Barrier on Silicon", J. Electrochem. Soc. 138(10) (October 1991), pp. 3062-3067</td> </tr> <tr> <td></td> <td>C21</td> <td colspan="2">"Cluster Tools for Fabrication of Advanced devices" Jap. J. of Applied Physics, Extended Abstracts, 22<sup>nd</sup> Conference Solid State Devices and Materials (1990), pp. 849 – 852 XP000178141</td> </tr> <tr> <td></td> <td>C22</td> <td colspan="2">"Applications of Integrated processing", Solid State Technology, US, Cowan Pub., Vol 37, No. 12 (December 1, 1994), pp. 45-47</td> </tr> <tr> <td></td> <td>C23</td> <td colspan="2">Kitigawa, et al., "Hydrogen-mediated low temperature epitaxy of Si in plasma-enhanced chemical vapor deposition", Applied Surface Science (2000), pp. 30-34</td> </tr> <tr> <td></td> <td>C24</td> <td colspan="2">Lee, et al., "Pulsed nucleation for ultra-high aspect ratio tungsten plugfill", Novellus Systems, Inc. (2001), pp. 1-2 (COPY NOT AVAILABLE TO APPLICANT AT THIS TIME)</td> </tr> <tr> <td></td> <td></td> <td colspan="2"></td> </tr> <tr> <td colspan="2">Examiner</td> <td colspan="2">Date Considered</td> </tr> <tr> <td colspan="4"> <p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.</p> </td> </tr> </table>				*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.			C16	Abstracts of articles – atomic layer deposition			C17	NERAC Search – Atomic Layer Deposition, search dated October 16, 2001			C18	Bader, et al., "Integrated Processing Equipment", Solid State Technology, Cowan Pub., Vol. 33, No. 5 (May 1, 1990), pp. 149-154			C19	Choi, et al., "The effect of annealing on resistivity of low pressure chemical vapor deposited titanium diboride", J. Appl. Phys. 69(11) (June 1, 1991), pp. 7853-7861			C20	Choi, et al., "Stability of TiB <sub>2</sub> as a Diffusion Barrier on Silicon", J. Electrochem. Soc. 138(10) (October 1991), pp. 3062-3067			C21	"Cluster Tools for Fabrication of Advanced devices" Jap. J. of Applied Physics, Extended Abstracts, 22 <sup>nd</sup> Conference Solid State Devices and Materials (1990), pp. 849 – 852 XP000178141			C22	"Applications of Integrated processing", Solid State Technology, US, Cowan Pub., Vol 37, No. 12 (December 1, 1994), pp. 45-47			C23	Kitigawa, et al., "Hydrogen-mediated low temperature epitaxy of Si in plasma-enhanced chemical vapor deposition", Applied Surface Science (2000), pp. 30-34			C24	Lee, et al., "Pulsed nucleation for ultra-high aspect ratio tungsten plugfill", Novellus Systems, Inc. (2001), pp. 1-2 (COPY NOT AVAILABLE TO APPLICANT AT THIS TIME)																						Examiner		Date Considered		<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.</p>			
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.																																																																					
	C16	Abstracts of articles – atomic layer deposition																																																																					
	C17	NERAC Search – Atomic Layer Deposition, search dated October 16, 2001																																																																					
	C18	Bader, et al., "Integrated Processing Equipment", Solid State Technology, Cowan Pub., Vol. 33, No. 5 (May 1, 1990), pp. 149-154																																																																					
	C19	Choi, et al., "The effect of annealing on resistivity of low pressure chemical vapor deposited titanium diboride", J. Appl. Phys. 69(11) (June 1, 1991), pp. 7853-7861																																																																					
	C20	Choi, et al., "Stability of TiB <sub>2</sub> as a Diffusion Barrier on Silicon", J. Electrochem. Soc. 138(10) (October 1991), pp. 3062-3067																																																																					
	C21	"Cluster Tools for Fabrication of Advanced devices" Jap. J. of Applied Physics, Extended Abstracts, 22 <sup>nd</sup> Conference Solid State Devices and Materials (1990), pp. 849 – 852 XP000178141																																																																					
	C22	"Applications of Integrated processing", Solid State Technology, US, Cowan Pub., Vol 37, No. 12 (December 1, 1994), pp. 45-47																																																																					
	C23	Kitigawa, et al., "Hydrogen-mediated low temperature epitaxy of Si in plasma-enhanced chemical vapor deposition", Applied Surface Science (2000), pp. 30-34																																																																					
	C24	Lee, et al., "Pulsed nucleation for ultra-high aspect ratio tungsten plugfill", Novellus Systems, Inc. (2001), pp. 1-2 (COPY NOT AVAILABLE TO APPLICANT AT THIS TIME)																																																																					
Examiner		Date Considered																																																																					
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.</p>																																																																							

13 2001

CR3D

DOCKET No.:	<u>Appm 15351</u>
SERIAL No.:	<u>09/1895, 6009</u>
FILED:	<u>20 JUNE 2001</u>
APPLICANT:	<u>Affiliated Metacinders</u>
INVENTOR:	<u>Mark, et al.</u>

The Patent & Trademark Office acknowledges and has stamped  
hereon the date of receipt of the items checked below which were  
mailed May 2002

AFFIDAVIT

DOCKET No.:	Appm 15351
SERIAL No.:	091895,609
FILED:	20 JUNE, 2001
APPLICANT:	<u>Affiled Metacinder</u>
INVENTOR:	<u>Mark, et al.</u>
The Patent & Trademark Office acknowledges and has stamped hereon the date of receipt of the items checked below which were mailed <u>July 2002</u>	
<input type="checkbox"/> AFFIDAVIT	
<input type="checkbox"/> AMENDMENT	
<input type="checkbox"/> APPLICATION PAPERS - OATH/DECLARATION	
<input type="checkbox"/> TOTAL CLS. _____ IND. CLS. _____ FEE \$ _____	
<input type="checkbox"/> SHEET(S) OF DRAWING(S) FORMAL/INFORMAL	
<input type="checkbox"/> ASSIGNMENT-RECORDAL FEE \$ _____	

DOCKET No.:	<u>AppM 15351</u>	INVENTOR:	<u>Applicant: Agi</u>	DOCKET No.:	<u>AppM 15351</u>	INVENTOR:	<u>Applicant: Agi</u>
SERIAL No.:	<u>0219951009</u>	DOCKET No.:	<u>AppM 15351</u>	SERIAL No.:	<u>0219951009</u>	DOCKET No.:	<u>AppM 15351</u>
FILED:	<u>20 JUNE 2001</u>	SERIAL No.:	<u>0219951009</u>	FILED:	<u>20 JUNE 2001</u>	SERIAL No.:	<u>0219951009</u>
		FILED:	<u>20 JUNE 2001</u>			FILED:	<u>20 JUNE 2001</u>
		APPLICANT:	<u>Applied Materials</u>			APPLICANT:	<u>Applied Materials</u>
		AFFIDAVIT	<u>I, Agi, declare that I am the inventor of the above invention and that I have full power and authority to make this declaration.</u>			AMENDMENT	<u>I, Agi, declare that I have no amendment to file at this time.</u>
		APPLICATION PAF	<u>I, Agi, declare that I have filed no application prior to this application.</u>			TOTAL CLS.	<u>I, Agi, declare that there are no total claims in this application.</u>
		SHEET(S) O	<u>I, Agi, declare that there is one sheet in this application.</u>			ASSIGNMENT-RE	<u>I, Agi, declare that there is no assignment or recordation in this application.</u>
<p>The Patent &amp; Trademark Office acknowledges and has stamped hereon the date of receipt of the items checked below which were mailed _____</p> <p><u>2 May 2002</u></p>							

<input type="checkbox"/> BRIEF	<input type="checkbox"/> APPEAL NOTICE	<input type="checkbox"/> DECLARATION	<input type="checkbox"/> APPLICATION PAPERS - OATH/DECLARATION	<input type="checkbox"/> TOTAL CLS. _____ IND. CLS. _____	<input type="checkbox"/> FEE \$ _____
<input type="checkbox"/> TRADEMARK/SERVICE MARK	<input type="checkbox"/> ISSUE FEE - BASE LETTER - CHARGE LETTER	<input type="checkbox"/> PETITION	<input type="checkbox"/> PRELIMINARY AME INFORMATION DIS REQUEST FOR EX	<input type="checkbox"/> SHEET(S) OF DRAWING(S) FORMAL	<input type="checkbox"/> FEE \$ _____
			PETITION	<input type="checkbox"/> ASSIGNMENT-RECORDAL FEE \$ _____	
					
<input type="checkbox"/> BRIEF	<input type="checkbox"/> APPEAL NOTICE	<input type="checkbox"/> DECLARATION	<input type="checkbox"/> ISSUE FEE - BASE/BALANCE	<input type="checkbox"/> LETTER - CHARGE DEPOSIT ACCOUNT	<input type="checkbox"/> TRADEMARK/SERVICE MARK APPLICATION
<input type="checkbox"/> TRADEMARK/SERVICE MARK	<input type="checkbox"/> PETITION	<input type="checkbox"/> INFORMATION DIS	<input type="checkbox"/> REQUEST FOR EX	<input type="checkbox"/> LETTER	<input type="checkbox"/> PETITION
			PETITION	<input type="checkbox"/> TRADEMARK APPLICATION	<input type="checkbox"/> PRELIMINARY AMENDMENT
EX-104 FORM 104-A EX-104 FORM 104-B					
<input type="checkbox"/> EXPRESS MAIL # _____	<input type="checkbox"/> CHECK # _____	<input checked="" type="checkbox"/> INFORMATION DISCLOSURE STATEMENT (S-00P)	<input type="checkbox"/> REQUEST FOR EXTENSION OF TIME	<input type="checkbox"/> RESPONSE TO _____	<input type="checkbox"/> SPECIMENS
<input type="checkbox"/> CHECK # <u>Ex-104-A</u>	<input checked="" type="checkbox"/> CHECK # <u>Ex-104-B</u>				

<input type="checkbox"/> SMALL ENTITY	<input type="checkbox"/> IN THE AMOUNT OF \$
<input type="checkbox"/> CHECK # _____	<input type="checkbox"/> IN THE AMOUNT OF \$
<input type="checkbox"/> CHECK # _____	<input checked="" type="checkbox"/> <u>1449</u> , postcards
EXPRESS MAIL # <u>10878</u>	

OIP

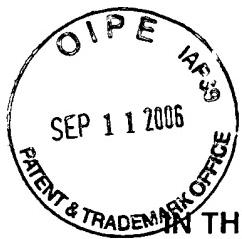
SEP 1 1991



Call Log #: 10878  
Date: 10/25/2011

SEP 11 2006

SEP 13 2006



PATENT  
Atty. Dkt. AMAT/5351/CPI/B/PJS

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Mak, et al.

§

Group Art Unit: 2812

Serial No.: 09/885,609

§

Confirmation No.: 5337

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

§

&lt;

If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/AMAT/5351/CPI/B/PJS/KMT.

Respectfully submitted,

*Keith M. Tackett*

Keith M. Tackett  
Registration No. 32,008  
MOSER, PATTERSON & SHERIDAN, L.L.P.  
3040 Post Oak Blvd., Suite 1500  
Houston, TX 77056  
Telephone: (713) 623-4844  
Facsimile: (713) 623-4846  
Attorney for Applicants

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No.	Serial No.
					AMAT/5351	09/885,609
<b>LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>					Applicant	Confirmation No. 5337
(Use several sheets if necessary)					Filing Date	Group
	Examiner Unknown				June 20, 2001	2812

**U.S. Patent Documents**

*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A1	4,486,487	12/04/84	Skarp	428	216	04/25/1983
	A2	4,829,022	05/09/89	Kobayashi et al.	437	107	12/09/1986
	A3	4,834,831	05/30/89	Nishizawa et al.	156	611	09/04/1987
	A4	4,838,983	06/13/89	Schumaker et al.	156	613	03/18/1988
	A5	4,838,993	06/13/89	Aoki et al.	156	643	12/03/1987
	A6	4,859,625	08/22/89	Nishizawa et al.	437	81	11/20/1987
	A7	4,927,670	05/22/1990	Erbil	427	255.3	06/22/1988
	A8	4,931,132	06/05/90	Aspnes et al.	156	601	10/07/1988
	A9	4,960,720	10/02/90	Shimbo	437	105	08/24/1987
	A10	4,975,252	12/04/90	Nishizawa et al.	422	245	05/26/1989
	A11	5,013,683	05/07/91	Petroff et al.	437	110	01/23/1989
	A12	5,085,885	02/04/92	Foley et al.	477	38	09/10/1990
	A13	5,091,320	02/25/92	Aspnes et al.	437	8	06/15/1990

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B1	01/66832 A2	09/13/2001	WO	C30B	16/44		X
	B2	01/40541 A1	06/07/2001	WO	C23C	16/40		X
	B3	01/36702 A1	05/25/2001	WO	C23C	16/00		X
	B4	01/29893 A1	04/26/2001	WO	H01L	21/768		X
	B5	01/29891 A1	04/26/2001	WO	H01L	21/768		X

**OTHER ART**

*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.
	C1	Hultman, et al., "Review of the thermal and mechanical stability of TiN-based thin films", <i>Zeitschrift Fur Metallkunde</i> , 90(10) (Oct. 1999), pp. 803-813.
	C2	Klaus, et al., "Atomic Layer Deposition of SiO <sub>2</sub> Using Catalyzed and Uncatalyzed Self-Limiting Surface Reactions", <i>Surface Review &amp; Letters</i> , 6(3&4) (1999), pp. 435-448.

Examiner	Date Considered
----------	-----------------

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

13 2006

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No. AMAT/5351		Serial No. 09/885,609	
<b>LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>					Applicant Mak, et al.		Confirmation No. 5337	
(Use several sheets if necessary)					Filing Date June 20, 2001		Group 2812	
<b>U.S. Patent Documents</b>								
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
	A14	5,246,536	09/21/93	Nishizawa et al.	156	610	03/10/1989	
	A15	5,254,207	10/19/93	Nishizawa et al.	156	601	11/30/1992	
	A16	5,296,403	03/22/94	Nishizawa et al.	437	133	10/23/1992	
	A17	5,311,055	05/10/94	Goodman et al.	257	593	11/22/1991	
	A18	5,316,615	05/31/94	Copel	117	95	03/09/1993	
	A19	5,348,911	09/20/94	Jurgensen et al.	117	91	04/26/1993	
	A20	5,438,952	08/08/1995	Otsuka	117	84	01/31/1994	
	A21	5,439,876	08/08/95	Graf et al.	505	447	08/16/1993	
	A22	5,441,703	08/15/95	Jurgensen	422	129	03/29/1994	
	A23	5,455,072	10/03/95	Bension et al.	427	255.7	11/18/1992	
	A24	5,469,806	11/28/95	Mochizuki et al.	117	97	08/20/1993	
	A25	5,503,875	04/02/96	Imai et al.	427	255.3	03/17/1994	
	A26	5,521,126	05/28/96	Okamura et al.	437	235	06/22/1994	
	A27	5,527,733	06/18/96	Nishizawa et al.	437	160	02/18/1994	
<b>Foreign Patent Documents</b>								
*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B6	01/29280 A1	04/26/2001	WO	C23C	16/32		X
	B7	01/27347 A1	04/19/2001	WO	C23C	16/44		X
	B8	01/27346 A1	04/19/2001	WO	C23C	16/44		X
	B9	01/15220 A1	03/01/2001	WO	H01L	21/768		X
<b>OTHER ART</b>								
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.						
	C3	Yamaguchi, et al., "Atomic-layer chemical-vapor-deposition of silicon dioxide films with extremely low hydrogen content", <i>Appl. Surf. Sci.</i> , Vol. 130-132 (1998), pp. 202-207.						
	C4	George, et al., "Surface Chemistry for Atomic Layer Growth", <i>J. Phys. Chem.</i> , Vol. 100 (1996), pp. 13121-131.						
Examiner					Date Considered			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)				Docket No. AMAT/5351	Serial No. 09/885,609
<b>LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>				Applicant Mak, et al.	Confirmation No. 5337
(Use several sheets if necessary)				Filing Date June 20, 2001	Group 2812

**U.S. Patent Documents**

*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A28	5,540,783	07/30/96	Eres et al.	118	725	05/26/1994
	A29	5,601,651	02/11/97	Watabe	118	715	12/14/1994
	A30	5,616,181	04/01/97	Yamamoto et al.	118	723 ER	11/21/1995
	A31	5,641,984	06/24/97	Aftergut et al.	257	433	08/19/1994
	A32	5,644,128	07/01/97	Wollnik et al.	250	251	08/25/1994
	A33	5,707,880	01/13/98	Aftergut et al.	437	3	01/17/1997
	A34	5,747,113	05/05/98	Tsai	427	255.5	07/29/1996
	A35	5,749,974	05/12/98	Habuka et al.	118	725	07/13/1995
	A36	5,796,116	08/18/98	Nakata et al.	257	66	07/25/1995
	A37	5,807,792	09/15/98	Ilg et al.	438	758	12/18/1996
	A38	5,830,270	11/03/98	McKee et al.	117	106	08/05/1996
	A39	5,835,677	11/10/98	Li et al.	392	401	10/03/1996
	A40	5,855,675	01/05/99	Doering et al.	118	719	03/03/1997

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B10	00/79576 A1	12/28/2000	WO	H01L	21/205		X
	B11	00/79019 A1	12/28/2000	WO	C23C	16/00		X
	B12	00/63957 A1	10/26/2000	WO	H01L	21/205		X

**OTHER ART**

*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.
	C5	George, et al., "Atomic layer controlled deposition of SiO <sub>2</sub> and Al <sub>2</sub> O <sub>3</sub> using ABAB...binary reaction sequence chemistry", <i>Appl. Surf. Sci.</i> , Vol. 82/83 (1994), pp. 460-467.
	C6	Wise, et al., "Diethyldiethoxysilane as a new precursor for SiO <sub>2</sub> growth on silicon", <i>Mat. Res. Soc. Symp. Proc.</i> , Vol. 334 (1994), pp. 37-43.

Examiner	Date Considered
----------	-----------------

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No. AMAT/5351	Serial No. 09/885,609		
<b>LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>					Applicant Mak, et al.	Confirmation No. 5337		
(Use several sheets if necessary)					Filing Date June 20, 2001	Group 2812		
<b>U.S. Patent Documents</b>								
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
	A41	5,858,102	01/12/99	Tsai	118	719	02/14/1998	
	A42	5,904,565	05/18/1999	Nguyen, et al.	438	687	07/17/1997	
	A43	5,923,056	07/13/99	Lee et al.	257	192	03/12/1998	
	A44	5,923,985	07/13/99	Aoki et al.	438	301	01/14/1997	
	A45	5,925,574	07/20/99	Aoki et al.	437	31	04/10/1992	
	A46	5,942,040	08/24/99	Kim et al.	118	726	08/27/1997	
	A47	5,947,710	09/07/1999	Cooper, et al.	418	63	06/16/1997	
	A48	5,972,430	10/26/99	DiMeo, Jr. et al.	427	255.32	11/26/1997	
	A49	6,001,669	12/14/99	Gaines et al.	438	102	07/21/1992	
	A50	6,174,377	01/16/2001	Doering, et al.	118	729	01/04/1999	
	A51	6,174,809	01/16/2001	Kang, et al.	438	682	12/15/1998	
	A52	6,203,613	03/20/2001	Gates, et al.	117	104	10/19/1999	
	A53	6,207,302	03/27/2001	Sugiura, et al.	428	690	03/02/1998	
	A54	6,248,605	06/19/2001	Harkonen, et al.	438	29	06/02/1999	
<b>Foreign Patent Documents</b>								
*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B13	00/54320 A1	09/14/2000	WO	H01L	21/44		X
	B14	00/16377 A2	03/23/2000	WO	H01L	---		X
	B15	00/15881 A2	03/23/2000	WO	C30B	---		X
<b>OTHER ART</b>								
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.						
	C7	Niinisto, et al., "Synthesis of oxide thin films and overlayers by atomic layer epitaxy for advanced applications", <i>Mat. Sci. &amp; Eng.</i> , Vol. B41 (1996), pp. 23-29.						
	C8	Ritala, et al., "Perfectly conformal TiN and Al <sub>2</sub> O <sub>3</sub> films deposited by atomic layer deposition", <i>Chemical Vapor Deposition</i> , Vol. 5(1) (January 1999), pp. 7-9.						
Examiner					Date Considered			
<b>*EXAMINER:</b> Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No. AMAT/5351	Serial No. 09/885,609
<b>LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>					Applicant Mak, et al.	Confirmation No. 5337
(Use several sheets if necessary)					Filing Date June 20, 2001	Group 2812
Examiner Unknown						

**U.S. Patent Documents**

*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A55	6,270,572	08/07/2001	Kim, et al.	117	93	08/09/1999
	A56	6,287,965	09/11/2001	Kang, et al.	438	648	02/23/2000
	A57	6,291,876	09/18/2001	Stumborg, et al.	257	632	08/20/1998
	A58	6,305,314	10/23/2001	Sneh, et al.	118	723 R	12/17/1999
	A59	6,306,216	10/23/2001	Kim, et al.	118	725	07/12/2000
	A60	6,316,098	11/13/2001	Yitzchaik, et al.	428	339	03/23/1999
	A61	2001/0000866	05/10/2001	Sneh, et al.	118	723 R	11/29/2000
	A62	2001/0009140	07/26/2001	Bondestam, et al.	118	725	01/25/2001
	A63	2001/0011526	08/09/2001	Doering, et al.	118	729	01/16/2001
	A64	2001/0031562	10/18/2001	Raaijmakers, et al.	438	770	02/22/2001
	A65	2001/0034123	10/25/2001	Jeon, et al.	438	643	04/06/2001
	A66						
	A67						

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B16	99/41423 A2	08/19/1999	WO	C23C	---		X
	B17	96/18756 A1	06/20/1996	WO	C23C	16/08		X

**OTHER ART**

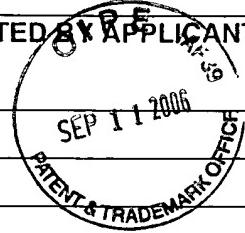
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.
	C9	Min, et al., "Atomic layer deposition of TiN thin films by sequential introduction of Ti precursor and NH <sub>3</sub> /sub3/", Symp.: Advanced Interconnects and Contact Materials and Processes for Future Integrated Circuits (Apr. 13-16, 1998), pp. 337-342.
	C10	Klaus, et al., "Atomic Layer Deposition of Tungsten using Sequential Surface Chemistry with a Sacrificial Stripping Reaction," Thin Solid Films 360 (2000), Pages 145 – 153, (Accepted Nov. 16, 1999).

Examiner	Date Considered
----------	-----------------

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No. AMAT/5351	Serial No. 09/885,609		
<b>LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>					Applicant Mak, et al.	Confirmation No. 5337		
(Use several sheets if necessary)					Filing Date June 20, 2001	Group 2812		
<b>U.S. Patent Documents</b>								
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
	A68							
	A69							
	A70							
	A71							
	A72							
	A73							
	A74							
	A75							
	A76							
<b>Foreign Patent Documents</b>								
*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B18	96/17107 A1	06/06/1996	WO	C23C	16/44		X
	B19	93/02111 A1	02/04/1993	WO	C08F	4/78		X
	B20	0 442 490 A1	08/21/1991	EP	C30B	25/02		X
	B21	0 344 352 A1	12/06/1989	EP	H01L	39/24		X
<b>OTHER ART</b>								
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.						
	C11	Min, et al., "Metal-Organic Atomic-Layer Deposition of Titanium-Silicon-Nitride Films", <i>Applied Physics Letters</i> , American Inst. Of Physics, Vol 75(11) (Sept. 13, 1999).						
	C12	Martensson, et al., "Atomic Layer Epitaxy of Copper on Tantalum", <i>Chemical Vapor Deposition</i> , 3(1) (Feb. 1, 1997), pp. 45-50.						
Examiner				Date Considered				
<p><b>*EXAMINER:</b> Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.</p>								

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. AMAT/5351	Serial No. 09/885,609
<b>LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>		Applicant Mak, et al.	Confirmation No. 5337
(Use several sheets if necessary)		Filing Date June 20, 2001	Group 2812
	Examiner Unknown		

**U.S. Patent Documents**

*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A77						
	A78						
	A79						
	A80						

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B22	62-091495 A	04/25/1987	JP	C30B	25/02		X
	B23	60-065712 A	04/15/1985	JP	C01B	33/113		X
	B24	03-048421	03/01/1991	JP	H01L	21/302		X
	B25	03-286531	12/17/1991	JP	H01L	21/316		X
	B26	04-031396 A	02/03/1992	JP	C30B	25/14		X
	B27	06-291048	10/18/1994	JP	H01L	21/205		X
	B28	08-264530	10/11/1996	JP	H01L	21/3205		X
	B29	11-269652	10/05/1999	JP	C23C	16/44		X

**OTHER ART**

*Examiner Initial	Including Author, Title, Date, Pertinent Pages, Etc.	
	C13	Ritala, et al. "Atomic Layer Epitaxy Growth of TiN Thin Films", <i>J. Electrochem. Soc.</i> , 142(8) (Aug. 1995), pp. 2731-737.
	C14	Elers, et al., "NbC15 as a precursor in atomic layer epitaxy", <i>Appl. Surf. Sci.</i> , Vol. 82/83 (1994), pp. 468-474.
	C15	Lee, "The Preparation of Titanium-Based Thin Film by CVD Using Titanium Chlorides as Precursors", <i>Chemical Vapor Deposition</i> , 5(2) (Mar. 1999), pp. 69-73.
	C16	Martensson, et al., "Atomic Layer Epitaxy of Copper, Growth & Selectivity in the Cu (II)-2,2,6,6-Tetramethyl-3, 5-Heptanedion ATE/H <sub>2</sub> Process", <i>J. Electrochem. Soc.</i> , 145(8) (Aug. 1998), pp. 2926-2931.

Examiner	Date Considered
----------	-----------------

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. AMAT/5351	Serial No. 09/885,609
<b>LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>		Applicant Mak, et al.	Confirmation No. 5337
(Use several sheets if necessary)		Filing Date June 20, 2001	Group 2812
	Examiner Unknown		

**U.S. Patent Documents**

*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A81						
	A82						
	A83						
	A84						
	A85						
	A86						
	A87						
	A88						

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B30	2001-62244	03/13/2001	JP	B01D	53/34		X
	B31	198 20 147	07/01/1999	DE	H01L	21/3205		X
	B32	196 27 017	01/09/1997	DE	H01L	21/283		X
	B33	2 626 110	07/21/1989	FR	H01L	39/24		X
	B34	2 692 597	12/24/1993	FR	C23C	16/00		X
	B35	2 355 727	05/02/2001	GB	C23C	16/44		X

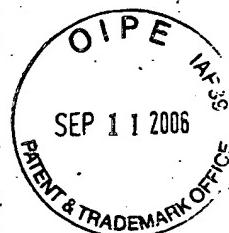
**OTHER ART**

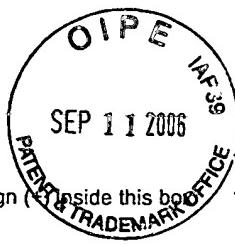
*Examiner Initial	Including Author, Title, Date, Pertinent Pages, Etc.		
	C17 Min, et al., "Chemical Vapor Deposition of Ti-Si-N Films with Alternating Source Supply", <i>Mat., Res. Soc. Symp. Proc.</i> , Vol. 564 (Apr. 5, 1999), pp. 207-210		
	C18 Bedair, "Atomic layer epitaxy deposition processes", <i>J. Vac. Sci. Technol.</i> 12(1) (Jan/Feb 1994)		
	C19 Yamaga, et al., "Atomic layer epitaxy of ZnS by a new gas supplying system in a low-pressure metalorganic vapor phase epitaxy", <i>J. of Crystal Growth</i> 117 (1992), pp. 152-155		
	C20 Elam, et al., "Nucleation and growth during tungsten atomic layer deposition on SiO <sub>2</sub> surfaces," <i>Thin Solid Films</i> 386 (2001) Pages 41 – 52, (Accepted Dec. 14, 2000).		

Examiner	Date Considered
----------	-----------------

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

DOCKET No.: <u>AMAT/5351</u>	DOCKET No.: <u>AMAT/5351</u>
SERIAL No.: <u>09/1885609</u>	SERIAL No.: <u>09/1885609</u>
FILED: <u>20 JUNE 2007</u>	FILED: <u>20 JUNE 2007</u>
APPLICANT: <u>Applied Materials, Inc.</u>	APPLICANT: <u>Applied Materials, Inc.</u>
INVENTOR: <u>MAK, et al.</u>	INVENTOR: <u>MAK, et al.</u>
The Patent & Trademark Office acknowledges and has stamped hereon the date of receipt of the papers checked below which were mailed <u>3/20/2007</u>	
<input type="checkbox"/> AFFIDAVIT <input type="checkbox"/> AMENDMENT <input type="checkbox"/> APPLICATION PAPERS - OATH/DECLARATION <input type="checkbox"/> APPLICATION PAPERS - OATH/DECLARATION <input type="checkbox"/> TOTAL CLS. _____ IND. CLS. _____ FEE \$ _____ <input type="checkbox"/> SHEET(S) OF DRAWING(S) FORMAL/INFORMAL <input type="checkbox"/> SHEET(S) OF DRAWING(S) FORMAL/INFORMAL <input type="checkbox"/> ASSIGNMENT-RECORDAL FEE \$ _____ <input type="checkbox"/> ASSIGMENT-RECORDAL FEE \$ _____	
<input type="checkbox"/> BRIEF <input type="checkbox"/> APPEAL NOTICE <input type="checkbox"/> DECLARATION <input type="checkbox"/> DECLARATION <input type="checkbox"/> ISSUE FEE - BASE/BALANCE <input type="checkbox"/> ISSUE FEE - BASE/BALANCE <input type="checkbox"/> LETTER - CHARGE DEPOSIT ACCOUNT <input type="checkbox"/> LETTER - CHARGE DEPOSIT ACCOUNT <input type="checkbox"/> TRADEMARK/SERVICEMARK APPLICATION <input type="checkbox"/> TRADEMARK/SERVICEMARK APPLICATION <input type="checkbox"/> PETITION <input type="checkbox"/> PETITION <input type="checkbox"/> PRELIMINARY AMENDMENT <input type="checkbox"/> PRELIMINARY AMENDMENT <input type="checkbox"/> INFORMATION DISCLOSURE STATEMENT (S) <u>Amendment</u> <input type="checkbox"/> INFORMATION DISCLOSURE STATEMENT (S) <input type="checkbox"/> REQUEST FOR EXTENSION OF TIME <input type="checkbox"/> REQUEST FOR EXTENSION OF TIME <input type="checkbox"/> RESPONSE TO _____	
<input type="checkbox"/> LETTER <input type="checkbox"/> TRADEMARK/SERVICEMARK APPLICATION <input type="checkbox"/> SMALL ENTITY <input type="checkbox"/> SMALL ENTITY <input type="checkbox"/> REQUEST FOR EXTENSION OF TIME <input type="checkbox"/> REQUEST FOR EXTENSION OF TIME <input type="checkbox"/> SPECIMENS <input type="checkbox"/> SPECIMENS <input type="checkbox"/> CHECK # <u>2100</u> IN THE AMOUNT OF \$ <u>100.00</u> <input type="checkbox"/> CHECK # <u>2100</u> IN THE AMOUNT OF \$ <u>100.00</u> <input type="checkbox"/> EXPRESS MAIL # <u>100.00</u> <input type="checkbox"/> EXPRESS MAIL # <u>100.00</u>	





Please type a plus sign (+) inside this box → +

PTO/SB/21 (08-00)

Approved for use through 10/31/2002. OMB 0651-0031

U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paper Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number.

# TRANSMITTAL FORM

(to be used for all correspondence after initial filing)

		Application Number	09/885,609
		Filing Date	Jun 20, 2001
		First Named Inventor	Mak, Alfred W.
		Group Art Unit	2812
		Examiner Name	Unknown
Total Number of Pages in This Submission	8	Attorney Docket Number	5351/AMI-00-12

## ENCLOSURES (check all that apply)

<input type="checkbox"/> Fee Transmittal Form	<input type="checkbox"/> Assignment Papers (for an Application)	<input type="checkbox"/> After Allowance Communication to Group
<input type="checkbox"/> Fee Attached	<input checked="" type="checkbox"/> Drawings (six sheets formal)	<input type="checkbox"/> Appeal Communication to Board of Appeals and Interferences
<input type="checkbox"/> Amendment / Reply	<input type="checkbox"/> Licensing-related Papers	<input type="checkbox"/> Appeal Communication to Group (Appeal Notice, Brief, Reply Brief)
<input type="checkbox"/> After Final	<input type="checkbox"/> Petition	<input type="checkbox"/> Proprietary Information
<input type="checkbox"/> Affidavits/declaration(s)	<input type="checkbox"/> Petition to Convert to a Provisional Application	<input type="checkbox"/> Status Letter
<input type="checkbox"/> Extension of Time Request	<input type="checkbox"/> Power of Attorney, Revocation Change of Correspondence Address	<input checked="" type="checkbox"/> Other Enclosure(s) (please identify below):
<input type="checkbox"/> Express Abandonment Request	<input type="checkbox"/> Terminal Disclaimer	1. Return Receipt Postcard to Kenneth C. Brooks
<input type="checkbox"/> Information Disclosure Statement	<input type="checkbox"/> Request for Refund	2. Return Receipt Postcard to Applied Materials, Inc.
<input type="checkbox"/> Certified Copy of Priority Document(s)	<input type="checkbox"/> CD, Number of CD(s)	3. Drawing Transmittal Letter
<input type="checkbox"/> Response to Missing Parts/ Incomplete Application	Remarks	
<input type="checkbox"/> Response to Missing Parts under 37 CFR 1.52 or 1.53		

## SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT

Firm or Individual name	Law Office of Kenneth C. Brooks
Signature	
Date	November 27, 2001

## CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231 on this date: 11-27-2001

Type or printed name	Jennifer Bonham
Signature	
Date	November 27, 2001

Burden Hour Statement: This form is estimated to take 0.2 hours to complete. Time will vary depending upon the needs of the individual case. Any comments on the amount of time you are required to complete this form should be sent to the Chief Information Officer, Patent and Trademark Office, Washington, DC 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Assistant Commissioner for Patents, Washington, DC 20231.

SEP 13 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

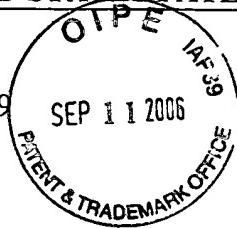
Applicants: Mak, et al

Application No.: 09/885,609

Filed: 6/20/2001

Title: System and Method to Form a  
Composite Film Stack Utilizing  
Sequential Deposition Techniques

Attorney Docket No.: 5351/AMI-00-12



Group Art Unit:  
2812

Examiner:  
Unknown

Assistant Commissioner for Patents  
Washington, D.C. 20231

**DRAWING TRANSMITTAL LETTER**

Sir:

Enclosed herewith please find:

- ( ) \_\_\_\_\_ sheets of redlined drawing(s) which indicate proposed changes to the drawing(s). Upon approval of these proposed changes, formal drawing(s) will be submitted.
- ( ) \_\_\_\_\_ sheets of corrected formal drawing(s), as required by the Notice of Patent Drawings Objection (PTO-948) which accompanied the Office Action dated \_\_\_\_\_.
- ( ) \_\_\_\_\_ sheets of corrected formal drawing(s), as required by the Notice of Patent Drawing(s) Objection (PTO-948) and approved in the Notice of Allowability dated \_\_\_\_\_.
- (✓) 6 \_\_\_\_\_ sheets of formal drawings. Please substitute these formal drawings for the informal drawings originally filed.

Examiner's approval of the entry of these drawings is respectfully requested. No new matter has been added.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231.

Date of Deposit: November 27, 2001

Typed Name: Jennifer Bonham

Signature:

Respectfully Submitted,

By   
Kenneth C. Brooks

Attorney/Agent for Applicant(s)  
Reg. No. 38,393

Date: November 27, 2001

SEP 13 2006

Telephone No.: 512 527-0104

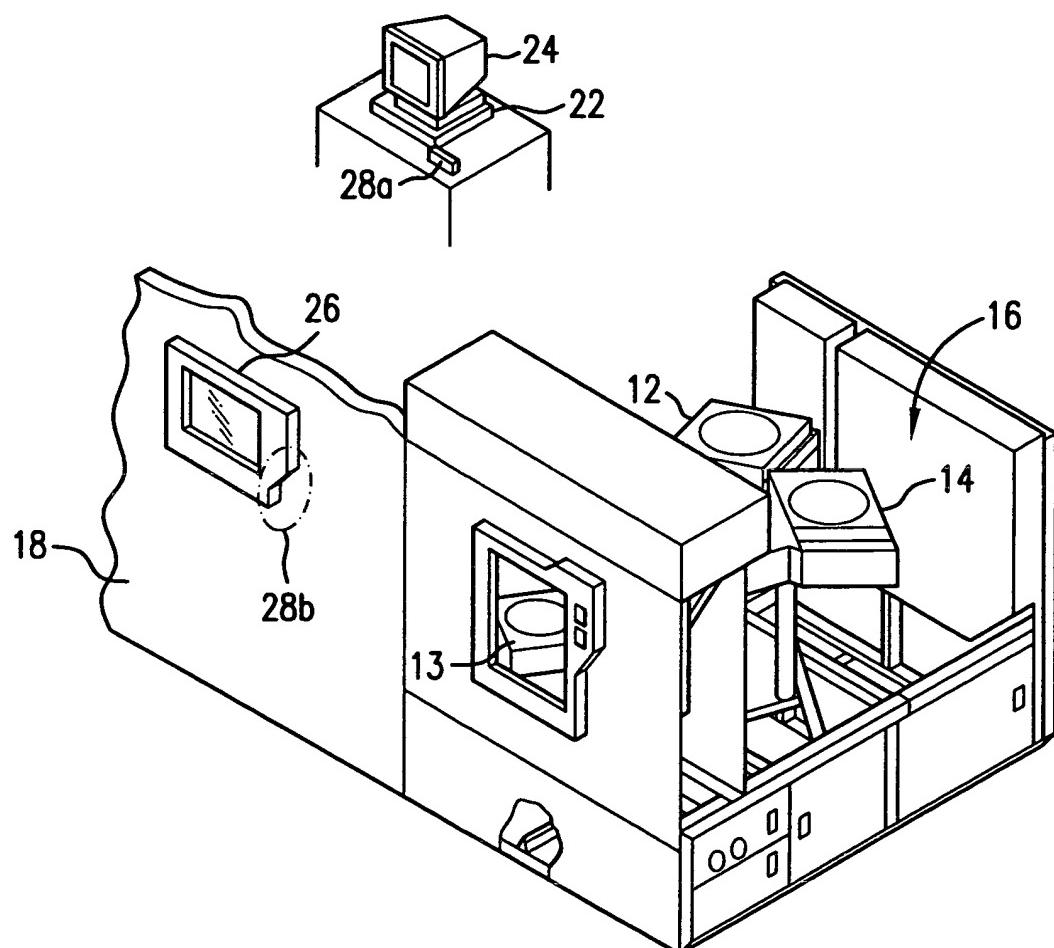
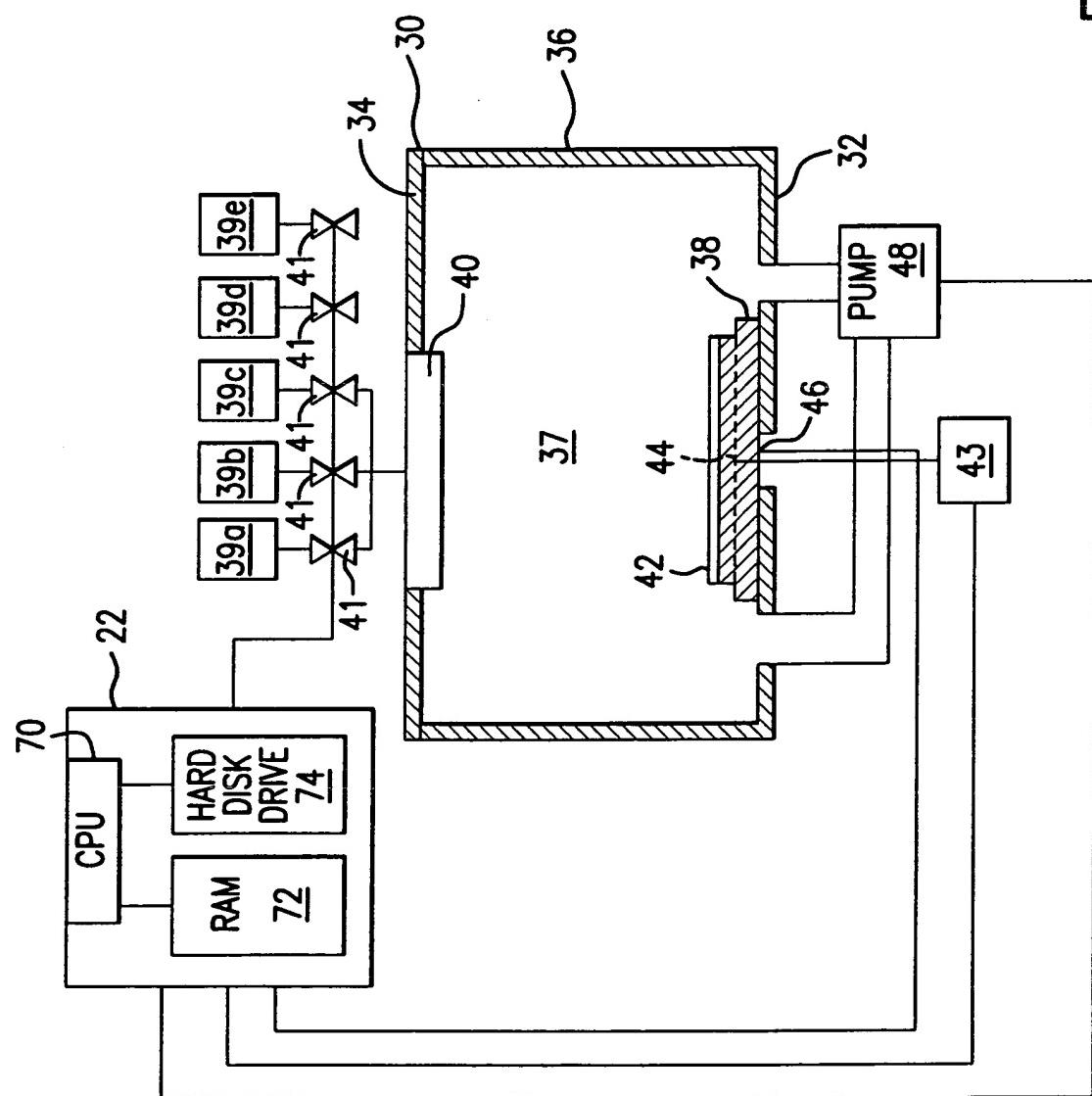


FIG. 1

FIG. 2



SEP 13 2006

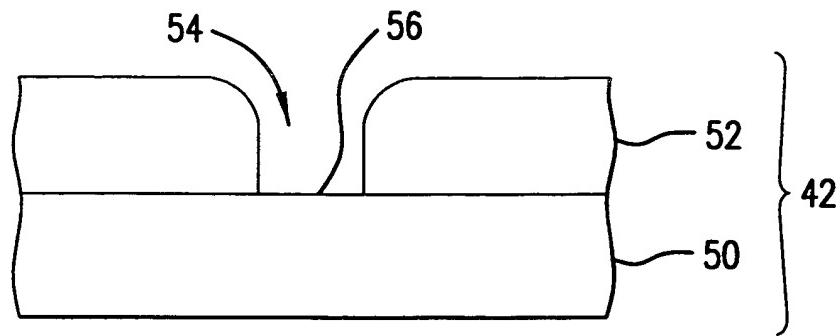


FIG. 3

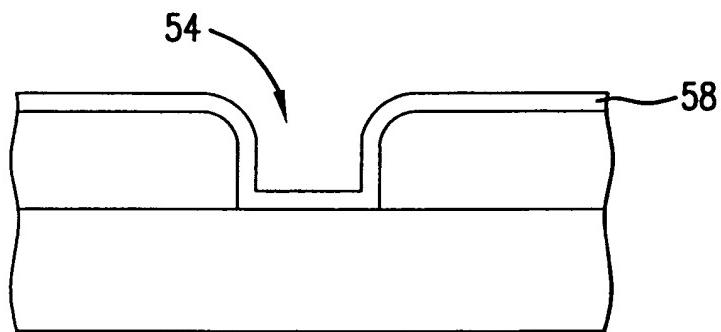


FIG. 4

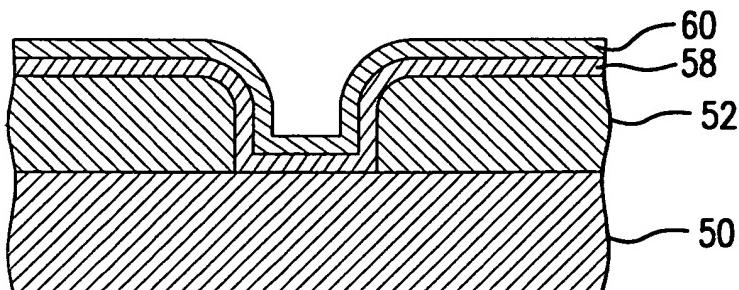


FIG. 5

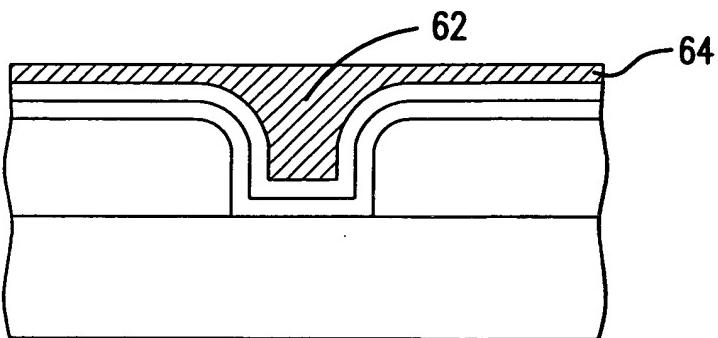


FIG. 6

SEP 13 2001

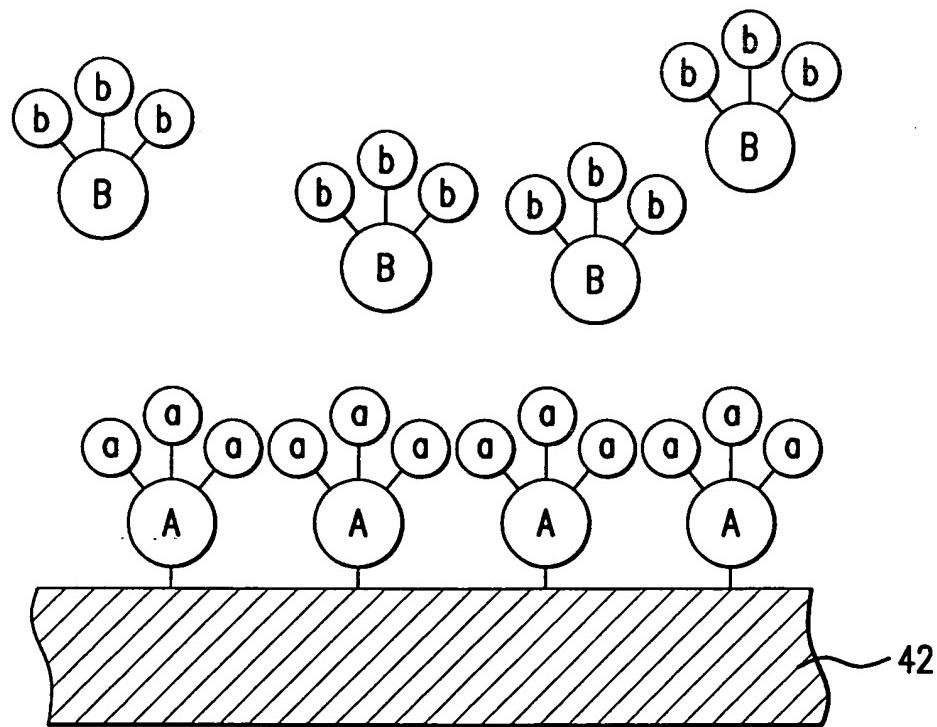


FIG. 7

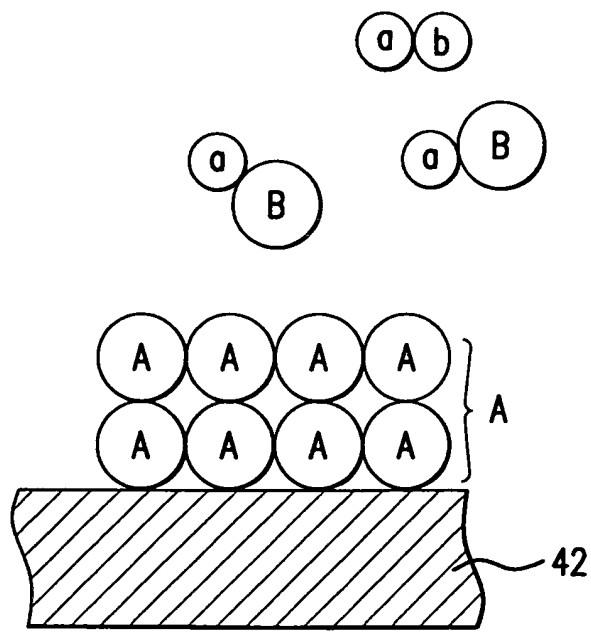


FIG. 8

SEP 13 2001

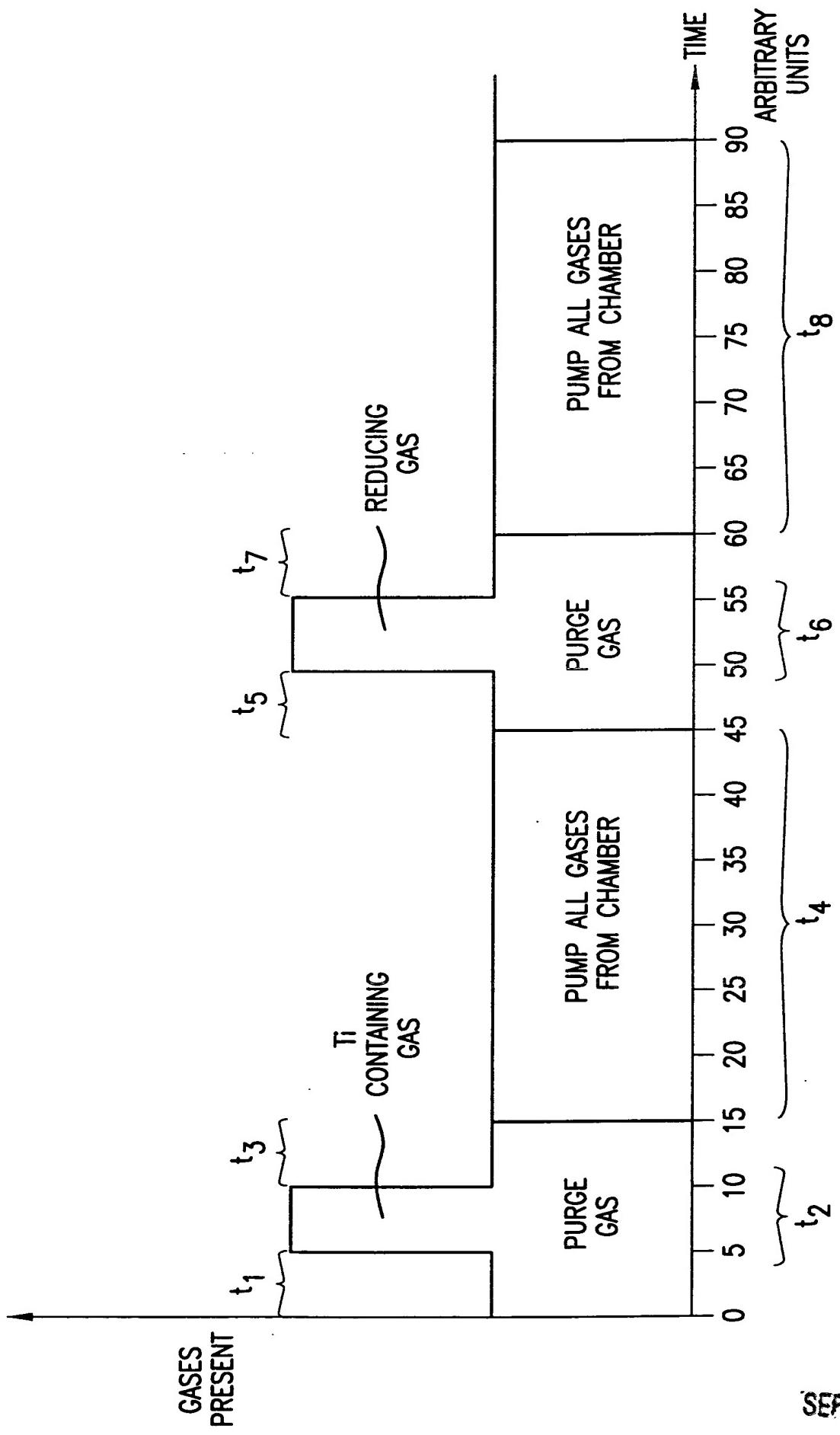


FIG. 9

SEP 13 2008

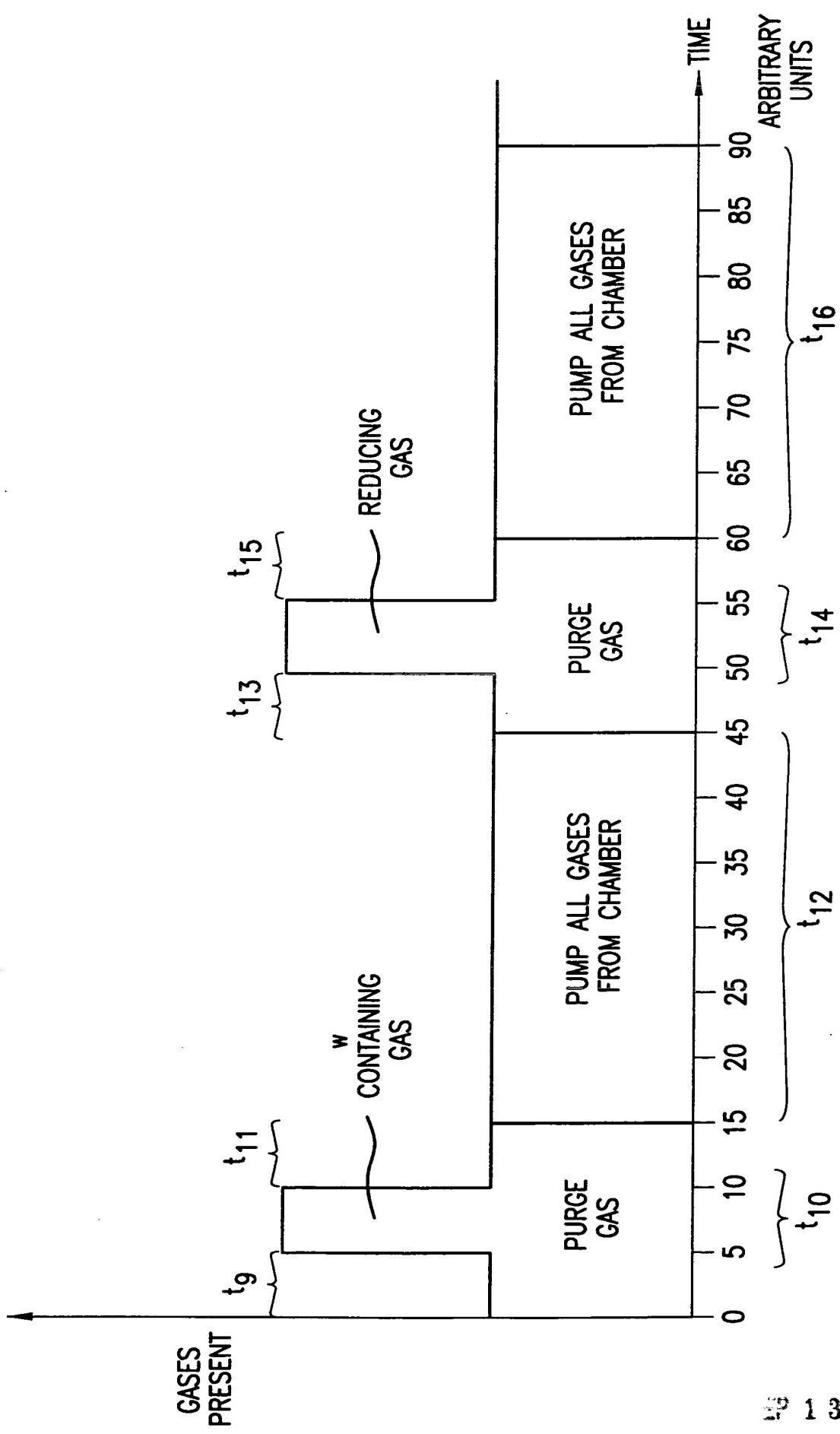
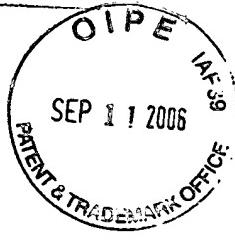


FIG. 10

BOX PATENT APPLICATION  
Commissioner for Patents  
Washington, D.C. 20231



Applicant: Mak et al.

Assignee: Applied Materials, Inc.

Title: SYSTEM AND METHOD TO FORM A COMPOSITE FILM STACK UTILIZING  
SEQUENTIAL DEPOSITION TECHNIQUES

Serial No. 09/885,609

Filed: 06/20/01

Attorney Docket No.: 5351/AMI-00-12

- Transmittal Form
- Letter to Chief Draftsperson
- Six sheets of formal drawings
- Return Receipt postcard to Kenneth C. Brooks
- Return Receipt postcard to Applied Materials

Dated: November 27, 2001

BOX PATENT APPLICATION  
Commissioner for Patents  
Washington, D.C. 20231



Applicant: Mak et al.

Assignee: Applied Materials, Inc.

Title: SYSTEM AND METHOD TO FORM A COMPOSITE FILM STACK UTILIZING  
SEQUENTIAL DEPOSITION TECHNIQUES

Serial No. 09/885,609

Filed: 06/20/01

Attorney Docket No.: 5351/AMI-00-12

- Transmittal Form
- Letter to Chief Draftsperson
- Six sheets of formal drawings
- Return Receipt postcard to Kenneth C. Brooks
- Return Receipt postcard to Applied Materials

Dated: November 27, 2001

BEST AVAILABLE COPY